



**PLATHINIUM**  
PLASMA THIN FILM INTERNATIONAL UNION MEETING

**22-26 September 2025**  
**Antibes, French Riviera**

# FINAL PROGRAM & EXHIBITORS GUIDE



**SFV** ORGANIZED BY  
Société Française du Vide

[www.plathinium.com](http://www.plathinium.com)

# Your one-stop shop for efficient and optimized vacuum.

01

## SOLUTIONS FOR COMPLEX SURFACES & SYSTEMS

### Coating Development

- Thin films on complex 3D geometries

### Hardware Innovation

- Custom coaters, plasma regulators, lithium sources

### Coating Services

- On-demand jobs, on-site process transfer

### Surface Characterization

- Advanced analysis capabilities



02

## ADVANCED COATINGS ON POWDERS

- Coating powders from nanometers to centimeters
- Tailored surface properties for industry-ready applications

03

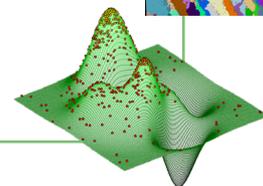
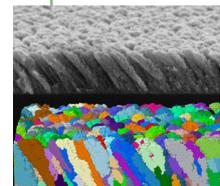
## SIMULATION TOOLS – DESIGN. PREDICT. OPTIMIZE.

**Virtual Coater™** | Optimize your process & results.

- *Your ally in cutting R&D time and cost.*

**Optima™** | Optimize your optical coating.

- *Your partner in reaching your ideal coating performance.*



Discover how ICS expertise can elevate your coating results and operations.





# PLATHINIUM

PLASMA THIN FILM INTERNATIONAL UNION MEETING

22 – 26 September 2025

Antibes, French Riviera

**[www.plathinium.com](http://www.plathinium.com)**

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# WELCOME

The PLASMA THIN film International Union Meeting (PLATHINIUM) is a biennial scientific conference that provides a unique forum for exchanging knowledge in the fields of low-temperature plasmas and thin films. It offers tutorials for students and fosters synergies between academia, research, and industry.

PLATHINIUM was created in 2019 through the merger of three former events - CIP (International Colloquium on Plasma Processes), ITFPC (Innovation in Thin Film Processing and Characterization), and MIATEC (Magnetron, Ion and Arc Technology) - and is now on its 4<sup>th</sup> edition. Today, it stands as a recognised meeting that emphasising both established and emerging applications, including thin films and coatings for microelectronics, automotive, and aeronautic industries, as well as the use of plasmas, thin films, and nanostructures in environmental, energy, biomedical, and agricultural domains.

PLATHINIUM 2025 takes place in Antibes, continuing the tradition of being a leading venue for advancing low-temperature plasma and thin film science and technology.

The 2025 scientific program will cover the following topics:

- **AMELI** / Plasma and/in liquids interaction: fundamentals and applications, plasmas for agriculture, bio-medicine, environment, green chemistry
- **DEPOS** / Plasma-assisted deposition, coatings and layers: fabrication process, characterizations, optical, electrical, tribological, catalytic and others applications
- **GROM** / Thin film growth and modelling (for plasma and others processes) including new data science and artificial intelligence approaches
- **ITEC** / Innovative applications, solutions and technologies (industrial, startup)
- **MODIDD** / Modelling, diagnostics and data-driven optimization of plasma processes: plasma modelling, processing, and diagnostics (optical, electrical, and laser-based diagnostic techniques and innovative data processing approaches (artificial intelligence, large language models (LLM), and digital twins) for low and high-pressure plasmas, as well as laser-produced plasmas and various discharge types (DC, RF, MW, DBD)
- **NANO** / Plasma nanotechnologies: nanomaterials, nanostructured thin films, dusty and misty plasmas, nucleation and growth...
- **PSURF** / Plasma surface processing, plasma etching, atomic layer processing, surface nanostructuring, surface functionalization

Have a fruitful event and a pleasant stay in Antibes and the French Riviera!

Welcome at 4<sup>th</sup> PLATHINIUM!

**Vasco GUERRA**  
Chair of the Scientific Committee

**Corinne CHAMPEAUX**  
Chair of the Steering Committee





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## GENERAL INFORMATION

### Practical information

- **Official language**

The conference language is English.

- **Wi-Fi access**

Indicated on your badge provided onsite.

- **Badges**

All delegates, exhibitors and visitors must wear their badges at all times to obtain admittance to the conference venue.

- **Mobile phone**

Please keep your mobile phone turned off or in silent mode in all conference rooms.

- **Publication**

The final program and the abstract book are sent in PDF to all registered participants via a download link.

- **Tourism Office**

Antipolis Convention Centre – level 1  
60 chemin des Sables  
06160 Juan-les-Pins

Phone: +33 (0)4 22 10 60 01 (press 1)  
[www.antibesjuanlespins.com/en](http://www.antibesjuanlespins.com/en)

- **Opening hours**

**Welcome desk – level 2**

Monday 22 Sept	08:30 – 20:00
Tuesday 23 Sept	08:30 – 20:00
Wednesday 24 Sept	08:15 – 18:30
Thursday 25 Sept	08:15 – 18:00
Friday 26 Sept	08:15 – 12:00

**Exhibition – level 2**

Tuesday 23 Sept	09:30 – 20:30
Wednesday 24 Sept	09:00 – 18:30

### Disclaimer

The program is preliminary. The organizers reserve the right to alter the program if and as is deemed necessary.

The PLATHINIUM 2025 organization and/or its agents have the right for any reason beyond their control to alter or to cancel, without prior notice, the Conference or any of the arrangements, timetables, plans or other items relating directly or indirectly to the Conference. The PLATHINIUM 2025 organization and/or its agents shall not be liable for any loss, damage, expenditure or inconvenience caused as a result of such alteration or cancellation.

### Contacts



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## SOCIAL EVENTS

### Get together parties

✓ Included in the registration – no booking necessary

- **Welcome reception**

Monday 22 September – 18:30 - 20:00

On Monday evening, after the short courses, come to pick your badge and conference material. The organization offers a cocktail to get together over a drink with other attendees.

- **Poster party session #1 and Industrial evening**

Tuesday 23 September – 17:30 - 20:30

At the end of the first day of the conferences, during the Poster session #1, all the exhibitors will be pleased to welcome you with a dinner cocktail.

- **Poster party - session #2**

Wednesday 24 September – 17:35 - 18:30

Finish the last but one day relaxed: after the afternoon break, let's talk with the presenters, of the poster session #2, about their work while having a friendly drink.

- **Conference dinner cocktail**

Thursday 25 September – 19:30 - 22:30

Enjoy a relaxed moment during the cocktail reception offered on the 3<sup>rd</sup> floor of the Palais des Congrès with its panoramic terrace and a musical entertainment



## Social activities

Friday 26 September from 14:00

✓ *Included in the registration / Booking mandatory*

### ▪ **Option #1 - Excursion to Grasse**

International capital of Flowers and Perfume

- 14:00 / Transfer by bus from to Grasse
- 15:00 / Guided tour of the Fragonard Perfume Factory
- 16:15 / Guided tour of Grasse old town
- 17:45 / Transfer back to Juan-les-Pins

The town of Grasse is said to be the core of the Riviera as well as a model of Provençal culture. The city offers splendid vistas over the shores near Cannes. A “Cité d’Art & d’Histoire,” Grasse is known as the “Capital of Flowers and Perfume.” Clinging to sun drenched hills, this place slowly reveals its charms to those who linger in its picturesque alleyways and welcoming little squares. The historic centre confirms this architectural quality. In the 18<sup>th</sup> century, perfume making, which took over from the tanneries, blossomed. In the 19<sup>th</sup> century, flower cultivation and perfume production gave Grasse its international reputation. You will visit one of the oldest perfume factories established in a 19<sup>th</sup> century building in the heart of the old town where perfumes and soaps are crafted everyday.

### ▪ **Option #2 - Walking tour on the coastal path “sentier de Tire-Poil”**

Immerse in the nature of the Cap d’Antibes

- 14:00 / Transfer from the Congress site to a bus tour around the Cap d’Antibes
- 14:45 / Hiking on the coastal path
- 17:15 / Transfer back to Juan-les-Pins

Discover with a guide the landscapes, the points of view and the remarkable species of the Tire-Poil path. Sea Lavendar, Jupiter Beard, Common Tern... these are the suggestive names which indicate the natural wealth of this little paradise on the Mediterranean coast. You will meet native and exotic plants and will learn to respect the protected species present on the Cap d’Antibes. A naturalistic, educational, playful and sports activity for everybody!



## PROGRAM INFORMATION

### Codes & topics

In the scientific program, the PLATHINIUM conference has been organized around 7 topics:

**AMELI Plasma and/in liquids interaction:**

*fundamentals and applications, plasmas for agriculture, bio-medicine, environment, green chemistry (decontamination/sterilization, depollution, gas conversion, bio-medical, treatments...)*

**DEPOS Plasma-assisted deposition, coatings and layers:**

*fabrication process, characterizations, optical, electrical, tribological, catalytic and others applications*

**GROMThin films growth and modelling** *(for plasma and others processes) including new data science and artificial intelligence approaches*

**ITEC Innovative applications, solutions and technologies**

*(industrial, startup)*

**MODIDDModelling, diagnostics and data-driven optimization of plasma**

**processes:** *plasma modelling, processing, and diagnostics (optical, electrical, and laser-based diagnostic techniques and innovative data processing approaches (artificial intelligence, large language models (LLM), and digital twins) for low and high-pressure plasmas, as well as laser-produced plasmas and various discharge types (DC, RF, MW, DBD)*

**NANOPlasma nanotechnologies:** *nanomaterials, nanostructured thin films, dusty and misty plasmas, nucleation and growth...*

**PSURF Plasma - surface processing,** *plasma etching, atomic layer processing, surface nanostructuration, surface fonctionnalization*

### Key to lecture

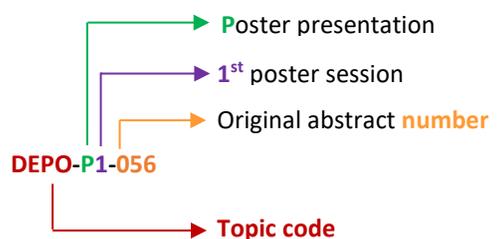
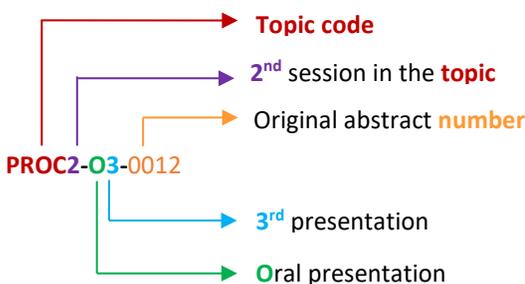
▪ **Type of presentations**

PL Plenary talk  
K Keynote lecture

O Oral presentation  
P Poster presentation

▪ **Lecture numbers**

▪ **Poster numbers**





## Instructions for authors

### ▪ Oral Presentations

#### Durations (including discussions)

- Plenary talk 40 minutes
- Keynote Lectures 30 minutes
- Oral Presentations 20 minutes

Lectures must be presented **in English**.

Each speaker must ensure that presentation (including 5 min for questions) is not longer than stipulated in the program. The chairpersons will be strict on timing.

**There is no preview system for the conference.** All speakers have to **load their presentation file on the laptop available on the session room, preferably on the half day before the start in the session room.**

PowerPoint projection will be available in the session rooms which are equipped with a laptop computer and a projector. Overhead projection and slide projection are not available. All the hardware will be provided by the Congress to ensure consistency in technical quality and allow for quick and smooth transition between the speakers.

Please note that **only the computers provided on site can be used.**

The video files attached to the presentation must be located in the same folder as the presentation files.

**Presentation's Privacy:** at the end of the Congress, ALL presentations and associated files will be deleted.

### ▪ Poster Presentations

Each poster must be in the size of **0.85 m in width and 1.2 m in height (A0)**.

The author's name and affiliation and the title of the paper must be indicated in the top section of the poster.

The posters will be presented and numbered according to the poster programme. The poster number will be displayed on top of the board. Writing or painting on the poster board is not allowed.

All posters will be displayed from Tuesday to Thursday evening.  
However, focus will be made with 2 poster sessions on:

- **P1 / Session #1** with industrial evening / Tuesday 23 from 17:30 until 19:30
- **P2 / Session #2** with refreshments / Wednesday 24 from 16:35 until 18:30

Presenters are expected to be next to their poster during the session (P1 or P2) assigned to their poster (information sent by email & available on the detailed program & registration space).

**Posters should be mounted from Tuesday 23 September 2025 at 10:00 and should be removed by 18:00 on Thursday 25 September 2025.**



Invited lectures

▪ **Plenary speakers**

In ANTIPOLIS AUDITORIUM

**Jones ALAMI**

PL6 // THU 25 – 14:00

Mohammed VI Polytechnic Univ. (MA)

*Tackling Lithium-ion battery challenges with PVD technologies*

**Marcela BILEK**

PL5 // THU 25 – 8:40

Univ. Sydney (AU)

*Plasma technologies advancing biomedicine and sustainability*

**Mariadriana CREATEORE**

PL2 // TUE 23 – 14:00

Univ. Eindhoven (NL)

*On novel merits of (plasma-assisted) atomic layer deposition for next-generation energy applications*

**Olivier GUAITELLA**

PL7 // FRI 26 – 08:40

LPP, Ecole Polytechnique, Palaiseau (FR)

*Plasma-catalyst interaction mechanisms for CO<sub>2</sub> recycling and molecule conversion*

**Amanda LIETZ**

PL3 // WED 24 – 8:40

NC State Univ., Raleigh (US)

*Plasma responses to tailored voltage waveforms in capacitively coupled plasmas*

**Ryo ONO**

PL4 // WED 24 – 14:00

Univ. Tokyo (JP)

*Fundamental diagnostics and modeling for streamer discharge and its application for cancer treatment*

**Mohan SANKARAN**

PL1 // TUE 23 – 09:25

Univ. Illinois, Urbana Champaign (US)

*Plasmas for ultrawide bandgap materials*



## ▪ Keynote speakers

### **Agnès GRANIER**

Univ. Nantes (FR)

ELLA FITZGERALD ROOM

NANO2-K1-010 // FRI 26 – 10:35

*Optimisation and in situ control of the deposition of nanocomposite thin films in low pressure misty plasma*

### **Satoshi HAMAGUCHI**

Univ. Osaka (JP)

ELLA FITZGERALD ROOM

PSURF2-K1-090 // TUE 23 – 16:15

*Numerical simulations and ion beam experiments for the analyses of surface reactions for reactive ion etching*

### **Rony SNYDERS**

Univ. Mons (BE)

ANTIPOLIS AUDITORIUM

ITEC3-K1-125 // FRI 26 – 10:35

*Study of CH<sub>4</sub> pyrolysis in a planar atmospheric gliding arc discharge*

### **Anne-Lise THOMANN**

Univ. Orléans (FR)

ANTIPOLIS AUDITORIUM

GROM2-K1-045 // TUE 23 – 16:15

*Metal thin films growth by magnetron sputter deposition in He: numerical and experimental approach*



Finalists for the SFV Michel Cantarel Student Grants

**Yanis AGHA**

LSPM, Univ. Sorbonne Paris-Nord, Villetaneuse **ELLA FITZGERALD ROOM**  
**MODIDD2-O2-093 // WED 24 – 10:55**  
*Description of H-atom absolute densities and sub-ns decay times in a pulsed microtube plasma jet using ps-TALIF and a streak camera*

**Aryan ARYAN**

GREMI – ICMN, Univ. Orléans (FR) **ELLA FITZGERALD ROOM**  
**NANO1-O1-028 // THU 25 – 16:55**  
*DC plasma-induced phase and morphological evolution of PtSn and PtRuSn nanoparticles produced in a magnetron-based gas aggregation source*

**Salah-Eddine BENRAZZOUQ**

IJL, Univ. Lorraine, Nancy (FR) **ANTIPOLIS AUDITORIUM**  
**DEPO1-O4-123 // TUE 23 – 11:35**  
*From temperature-independent to tunable resistivity of high-entropy alloys thin films*

**Robin DANTINNE**

ChIPS, UMonS (BE) **ANTIPOLIS AUDITORIUM**  
**PSURF5-O2-114 // THU 25 – 15:05**  
*Elucidating the growth mechanism of functionalized plasma polymer films using complex geometry substrates at various substrate temperatures*

**Mina FARAHANI**

Univ. West. Bohemia, Pilsen (CZ) **ELLA FITZGERALD ROOM**  
**MODIDD3-O2-054 // THU 25 – 15:05**  
*Enhancing energy flux to insulating surfaces using unipolar and bipolar HiPIMS pulse configurations*

**Marion GIREAU**

IRCER, Univ. Limoges (FR) **ELLA FITZGERALD ROOM**  
**NANO1-O3-086 // THU 25 – 17:35**  
*Novel nanocomposite thin films by pulsed laser processes for plasmonic based sensing of cancer markers*

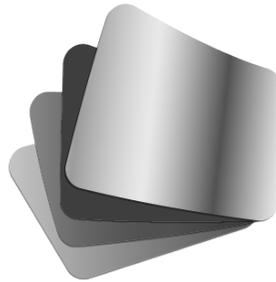
**Marianna ROGGIO**

CNR-NANOTEC, Univ. Bari (IT) **ANTIPOLIS AUDITORIUM**  
**DEPO6-O4-120 // THU 25 – 17:15**  
*Atmospheric pressure plasma-assisted deposition of zinc-based coatings for agriculture applications*

**Leila ZAHEDI**

CEPLANT, Masaryk Univ, Brno (CZ) **ANTIPOLIS AUDITORIUM**  
**PSURF5-O1-007 // THU 25 – 14:45**  
*Enhancing corrosion resistance of magnesium alloys with plasma treatment and electrospun biodegradable polymer coatings*





# PLATHINIUM

PLASMA THIN FILM INTERNATIONAL UNION MEETING

## DETAILED PROGRAM

- Tuesday 23 September
- Wednesday 24 September
- Thursday 25 September
- Friday 26 September



Tuesday 23 September

9:10 – 12:30

9:10 Opening ceremony ANTIPOLIS AUDITORIUM  
 V. Guerra, *Chair of Plathinium 2025*  
 C. Champeaux, *Chair of the Steering Committee of Plathinium 2025*

9:25 **PLENARY TALK II** Plasmas for ultrawide bandgap materials  
M. Sankaran  
*Univ. Illinois, Urbana-Champaign (US)*

10:05 COFFEE BREAK

**DEPO 1 Plasma-assisted deposition, coatings and layers** ANTIPOLIS AUDITORIUM

Chair: D. Hegemann (CH)

10:35 DEPO1-O1-077 • Minimizing the impact of negative oxygen ions on aluminium-doped zinc oxide thin films deposited by rotatable RF magnetron sputtering  
L. Villibord, E. Stamate  
*Technical Univ. Denmark Nanolab - Lyngby (DK)*

10:55 DEPO1-02-031 • Controlling the stoichiometry of copper oxides depending on operating parameters  
Y. Wang, F. Arefi-Khonsari, A. Pailleret, J. Pulpytel  
*Sorbonne Univ., CNRS, LISE, Paris (FR)*

11:15 DEPO1-O3-023 • Exploring energy transfer in sputter deposited tungsten films: effects of magnetic field strength and pressure-distance on phase composition  
F. Ahangarani Farahani, D. Depla  
*Department of Solid State Sciences, Ghent Univ., Ghent (BE)*

11:35 DEPO1-O4-123 • From temperature-independent to tunable resistivity of high-entropy alloys thin films  
S.-E. Benrazzouq, J. Ghanbaja, S. Migot, V. Milichko, J.F. Pierson  
*Univ. Lorraine, CNRS, IJL, Nancy (FR)*

11:55 DEPO1-05-035 • Reversible functionalization of citronellal plasma polymers - towards pH responsive thin films  
J. Carneiro de Oliveira, P. Covin, A. Airoudj, F. Bally-Le Gall, V. Roucoules  
*Univ. Haute-Alsace, Univ. Strasbourg, CNRS, IS2M UMR 7361, Mulhouse (FR)*

12:30 LUNCH



Tuesday 23 September

9:10 – 12:30

10:05 COFFEE BREAK

**AMELI 1 – Plasma and/in liquid interaction**

ELLA FITZGERALD ROOM

 Chair: M. Hori (JP)

- 10:35 AMELI1-O1-038 • On the occurrence of internal partial discharges inside aluminium matrix composite layers during plasma electrolytic oxidation process  
T. Czerwiec<sup>1</sup>, A. Maizeray<sup>1</sup>, G. Marcos<sup>1</sup>, M.P. Planche<sup>2</sup>, H. Liao<sup>2</sup>, G. Henrion<sup>1</sup>, J. Martin<sup>1</sup>  
<sup>1</sup> *Institut Jean Lamour, Univ. Lorraine - Nancy (FR)*  
<sup>2</sup> *Univ. Marie et Louis Pasteur, UTBM, ICB - Montbéliard (FR)*
- 10:55 AMELI1-O2-016 • Investigation of the chemical behaviour of an electrolytic discharge used to synthesize low-density mesoporous metals  
C. Boudat<sup>1</sup>, F. Durut<sup>1</sup>, R. Botrel<sup>1</sup>, T. Belmonte<sup>2</sup>  
<sup>1</sup> *Commissariat à l'Energie et aux Energies Alternatives (CEA), Valduc, Is sur Tille (FR)*  
<sup>2</sup> *Univ. Lorraine, CNRS, IJL, Nancy (FR)*
- 11:15 AMELI1-O3-103 • Degradation of methylene orange in aqueous solution using non-thermal plasma  
T. Nguyen, G. Henrion, L. Sonhafouo Mbantio, T. Gries, C. Noël  
*Institute Jean Lamour - Equipe Plasmas - Procédés - Surfaces - Nancy (FR)*
- 11:35 AMELI1-O4-102 • Plasma technology for tetrodotoxin inactivation in *Iagocephalus sceleratus* fishmeal  
S. Mouchtouris<sup>1, 2</sup>, G. Kokkoris<sup>1, 2</sup>, M. Kotsiri<sup>3</sup>, I. Kleidas<sup>3</sup>, T.I. Anastasiou<sup>3</sup>, E. Kagiampaki<sup>3</sup>, M. Mandalakis<sup>3</sup>, I. Nengas<sup>3</sup>  
<sup>1</sup> *School of Chemical Engineering, National Technical Univ. Athens - Athens (GR)*  
<sup>2</sup> *Inst. Nanoscience & Nanotechnology, NCSR "Demokritos" - Athens (GR)*  
<sup>3</sup> *Inst. Marine Biology, Biotechnology and Aquaculture, HCMR, Anavyssos & Heraklion (GR)*
- 11:55 AMELI1-O5-112 • Aerosol-assisted atmospheric pressure plasma deposition of active coatings based on natural antioxidant compounds  
A. Lanza<sup>1, 2</sup>, F. Palumbo<sup>2</sup>, N. De Vietro<sup>3</sup>, G. Mancini<sup>3</sup>, A. Milella<sup>1, 2</sup>, P. Favia<sup>1, 2</sup>  
<sup>1</sup> *Dpt. of Chemistry, Univ. Bari Aldo Moro - Bari (IT)*  
<sup>2</sup> *CNR-NANOTEC, C/o Dpt. of Chemistry, Univ. Bari Aldo Moro - Bari (IT)*  
<sup>3</sup> *Dpt. of Biosciences, Biotechnology and Environment, Univ. Bari Aldo Moro - Bari (IT)*

12:30 LUNCH



Tuesday 23 September

**14:00 – 15:45**
**ANTIPOLIS AUDITORIUM**

 Chair: L. Stafford (CA)

14:00 **PLENARY TALK //** On novel merits of (plasma-assisted) atomic layer deposition for next-generation energy applications

M. Creatore

*Eindhoven Univ. of Technology – Eindhoven (NL)*

**GROM 1 Thin film growth and modelling**

**ANTIPOLIS AUDITORIUM**

 Chair: R. Clergereaux (FR)

14:45 GROM1-O1-022 • The role of nitrogen additive on the growth of ultrathin silver films: in situ and real-time studies during magnetron sputtering deposition

D. Babonneau<sup>1</sup>, G. Abadias<sup>1</sup>, A. Michel<sup>1</sup>, F. Pailloux<sup>1</sup>, K. Solanki<sup>1</sup>, A. Coati<sup>2</sup>, Y. Garreau<sup>2,3</sup>, A. Resta<sup>2</sup>, A. Vlad<sup>2</sup>, M. Kaminski<sup>4</sup>, B. Krause<sup>4</sup>

<sup>1</sup> *Institut Pprime - Poitiers (FR)*

<sup>2</sup> *SOLEIL synchrotron - Gif-sur-Yvette (FR)*

<sup>3</sup> *Laboratoire Matériaux et Phénomènes Quantiques - Paris (FR)*

<sup>4</sup> *KIT, Institute of Photon Science and Synchrotron Radiation - Karlsruhe (DE)*

15:05 GROM1-O2-117 • Improving TiO<sub>2</sub> anatase crystallization using a low power dielectric barrier discharge at atmospheric pressure in a single step process: a precursor and parametric study

N. Fosseur<sup>1,2</sup>, S. Godet<sup>2</sup>, F. Reniers<sup>1</sup>

<sup>1</sup> *Chemistry of Surfaces, Interfaces and Nanomaterials, Faculty of Sciences, Univ. Libre Bruxelles (BE)*

<sup>2</sup> *4MAT, Engineering Faculty, Univ. Libre Bruxelles (BE)*

15:25 GROM1-O1-130 • Experimental and theoretical study of plasma polymerization into 3D structures

L. Zajickova<sup>1,3</sup>, D. Necas<sup>1</sup>, M. Janusova<sup>1</sup>, L. Janu<sup>1</sup>, P. De Navascues<sup>2</sup>, D. Hegemann<sup>2</sup>, N. Rusnakova<sup>3</sup>

<sup>1</sup> *CEITEC - Brno (CZ)*

<sup>2</sup> *EMPA - St. Gallen (CH)*

<sup>3</sup> *Masaryk Univ. - Brno (CZ)*

15:45

COFFEE BREAK



Tuesday 12 September

14:00 – 15:45

**PSURF 1 Plasma surface processing**

ELLA FITZGERALD ROOM

 Chair: T. Tillocher (FR)

- 14:45 PSURF1-O1-075 • Dry etch process development of gapless silicon nitride microlens array for CMOS imager sensors  
A. Tavernier<sup>1</sup>, F. Tomaso<sup>1</sup>, R. Coquand<sup>1</sup>, Z. Mehrez<sup>1</sup>, C. Bellegarde<sup>1</sup>,  
C. Sese<sup>1</sup>, L. Masarotto<sup>1</sup>, S. Guerroudj<sup>2</sup>  
<sup>1</sup> *Institut des Molécules et Matériaux du Mans, UMR 6283 CNRS, Univ. Le Mans (FR)*  
<sup>2</sup> *ECAM RENNES – Louis de Broglie, Campus de Ker Lann, Bruz (FR)*
- 15:05 PSURF1-O2-104 • Development of plasma ALE for  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> using the gas mixture SF<sub>6</sub>/Ar and CH<sub>4</sub>/H<sub>2</sub>  
H. Beji, C. Cardinaud, A. Girard, C. Mannequin  
*Institut des Matériaux Jean Rouxel de Nantes - Nantes (FR)*
- 15:25 PSURF1-O3-046 • Plasma cryogenic processes applied to SiO<sub>2</sub> deep etching  
R. Dussart<sup>1</sup>, T. Tillocher<sup>1</sup>, P. Lefauchaux<sup>1</sup>, L. Becerra<sup>1</sup>, L.J. Overzet<sup>2</sup>  
<sup>1</sup> *GREMI – Univ. Orléans - CNRS - Orléans (FR)*  
<sup>2</sup> *PSAL - UT Dallas - Richardson (US)*

15:45 COFFEE BREAK



Tuesday 12 September

16:15 – 17:20

**GROM 2 Thin film growth and modelling**

ANTIPOLIS AUDITORIUM

 Chair: L. Zajickova (CZ)

- 16:15 **KEYNOTE // GROM2-K1-045** • Metal thin films growth by magnetron sputter deposition in He: numerical and experimental approach  
A.-L. Thomann<sup>1</sup>, P. Brault<sup>1</sup>, T. Sauvage<sup>2</sup>, A. Fernandez<sup>3</sup>, A. Caillard<sup>1</sup>  
<sup>1</sup> GREMI (CNRS/Univ. Orléans) - Orléans (FR)  
<sup>2</sup> CEMHTI CNRS - Orléans (FR)  
<sup>3</sup> CSIC-Univ. Seville - Séville (ES)
- 16:45 GROM2-01-005 • Influence of the nature of the transition metal in oblique angle deposition  
A. Besnard, H. Gerami, N. Martin  
*Univ. Marie et Louis Pasteur, SUPMICROTECH, CNRS, Institut FEMTO-ST - Besançon (FR)*
- 17:05 GROM2-02-108 • Kinetic monte carlo simulation of hetero-epitaxial deposition of metal onto silicon substrate; influence of multistep deposition process  
C. Mastail, A. Muriel Sanchez, P. Polisetty, A. Michel, G. Abadias  
*Institut Pprime - Poitiers (FR)*

17:30 POSTER SESSION #1  
& INDUSTRIAL EVENING



Tuesday 23 September

16:15 – 17:30

**PSURF 2 Plasma surface processing**

ELLA FITZGERALD ROOM

 Chair: M. Creatore (NL)

- 16:15 **KEYNOTE // PSURF2-K1-090** • Numerical simulations and ion beam experiments for the analyses of surface reactions for reactive ion etching  
S. Hamaguchi  
*Univ. Osaka (JP)*
- 16:45 **PSURF2-O1-107** • Enhancing plasma etching efficiency via physics-based modeling, experimental measurements, machine learning, and optimization algorithms  
E. Boniakou<sup>1</sup>, S. Mouchtouris<sup>2</sup>, T. Boura<sup>3</sup>, C. Zormpa<sup>2</sup>, A. Kondi<sup>2</sup>,  
D. Belounis<sup>4</sup>, T. Giannakopoulos<sup>3</sup>, A. Armaou<sup>4</sup>, V. Constantoudis<sup>2</sup>,  
E. Gogolides<sup>2</sup>, G. Kokkoris<sup>1</sup>  
<sup>1</sup> *School of Chemical Engineering, National Technical Univ. of Athens - Athens (GR)*  
<sup>2</sup> *Institute of Nanoscience & Nanotechnology, NCSR Demokritos - Athens (GR)*  
<sup>3</sup> *Institute of Informatics & Telecommunications, NCSR Demokritos - Athens (GR)*  
<sup>4</sup> *Chemical Engineering Department, Univ. Patras - Patras (GR)*
- 17:05 **PSURF-O2-049** • Formation of black silicon microstructures by the stiger etching process for microfluidic applications  
A. Rahali, A. Stolz, L. Becerra, P. Lefauchaux, R. Dussart, T. Tillocher  
*GREMI, Univ. Orléans, CNRS UMR 7344 - Orléans (FR)*

17:30

POSTER SESSION #1  
& INDUSTRIAL EVENING



Wednesday 24 September

8:40 – 10:05

ANTIPOLIS AUDITORIUM

 Chair: S. Konstantinidis (BE)

8:40 **PLENARY TALK // Plasma responses to tailored voltage waveforms in capacitively coupled plasmas**

A. Lietz<sup>1</sup>, S. Zulqarnain<sup>1</sup>, N. Tabassum<sup>1</sup>, B. Peete<sup>1</sup>, J. Prager<sup>2</sup>, T. Ziemba<sup>2</sup>,  
P. Melnik<sup>2</sup>, J. Perry<sup>2</sup>, S. Shannon<sup>2</sup>

<sup>1</sup> North Carolina State Univ. - Raleigh (US)

<sup>2</sup> EHT Semi - Seattle (US)

**DEPO 2 Plasma-assisted deposition,  
coatings and layers**

ANTIPOLIS AUDITORIUM

 Chair: C. Costin (RO)

9:25 DEPO2-O1-121 • Erosion resistant PVD coatings on CFRP substrates

P. Abarca<sup>1,3</sup>, T. Maerten<sup>1</sup>, S. Belveze<sup>1</sup>, S. Guimond<sup>2</sup>, C. Jaoul<sup>3</sup>, P. Tristant<sup>3</sup>,  
M. Cavarroc<sup>4</sup>

<sup>1</sup> Oerlikon Balzers France (FR)

<sup>2</sup> Oerlikon Surface Solutions AG - Balzers (LI)

<sup>3</sup> Univ. Limoges (FR)

<sup>4</sup> Safran Tech - Paris (FR)

9:45 DEPO2-O2-067 • Extraordinary oxidation behavior of W-Zr thin-film metallic glasses: a route for tailoring functional properties of W-Zr-O films

P. Zeman, M. Cervena, J. Houska, S. Haviar, J. Rezek, S. Zuzjakova  
Department of Physics and NTIS - European Centre of Excellence, Univ. West Bohemia, Pilsen (CZ)

10:05

COFFEE BREAK



Wednesday 13 September

8:40 – 10:05

**MODIDD 1 Modelling, diagnostics and data-driven optimization of plasma processes**

ELLA FITZGERALD ROOM

 Chair: S. Konstantinidis (BE)

- 9:25 MODIDD1-O1-070 • Assisting plasma diagnostics with artificial intelligence methods: trends and applications in non-equilibrium plasmas operating from moderate-to-atmospheric pressures  
D. Stefanis<sup>1</sup>, G. Makrypodis<sup>2</sup>, K. Giotis<sup>2, 1</sup>, L. Invernizzi<sup>1</sup>, P. Svarnas<sup>2</sup>, G. Lombardi<sup>1</sup>, C. Lazzaroni<sup>1</sup>, K. Gazeli<sup>1</sup>  
<sup>1</sup> *LSPM—CNRS & Univ. Sorbonne Paris Nord - Villetaneuse (FR)*  
<sup>2</sup> *High Voltage Lab., Electrical & Computer Eng. Dept., Univ. Patras - Rion (GR)*
- 9:45 MODIDD1-O2-019 •  $\mu$ -second pulse and RF coupling in an APPJ  
A. Patelli<sup>1</sup>, R. Fiorotto<sup>1</sup>, E. Shakerinasab<sup>1</sup>, T. Habib<sup>2</sup>, B. Caillier<sup>2</sup>  
<sup>1</sup> *Univ. Padova (IT)*  
<sup>2</sup> *Lab. DPHE, Univ. Toulouse, INU Champollion, Albi (FR)*

10:05 COFFEE BREAK



Wednesday 24 September

**10:35 – 12:30****DEPO 3 Plasma-assisted deposition,  
coatings and layers****ANTIPOLIS AUDITORIUM**
 Chair: M. Sankaran (US)

- 10:35 DEPO3-O1-047 • Development and optimization of CrN coatings for enhanced tool performance in cryogenic machining of Ti<sub>6</sub>Al<sub>4</sub>V  
G. Chettouh<sup>1</sup>, S. Achache<sup>1</sup>, L. Gueye<sup>1</sup>, Y. Pinot<sup>2</sup>, F. Sanchette<sup>1</sup>, C. Nouveau<sup>2</sup>, M. El Garah<sup>1</sup>  
<sup>1</sup> LASMIS, Antenne de Nogent et LRC CEA-LASMIS, NICCI, Nogent (FR)  
<sup>2</sup> Arts et Métiers Institute of Technology, LABOMAP, HESAM Univ., Cluny (FR)
- 10:55 DEPO3-O2-083 • Enhanced morphology and ferroelectric properties of Sc<sub>0.3</sub>Al<sub>0.7</sub>N sputtered thin films via a compositionally graded layers  
T. Nguyen, D.T. Dao, M.S. Azeem, I. Nesterenko, M. Moridi, T. Xu  
 Silicon Austria Labs - Villach (AT)
- 11:15 DEPO3-O3-131 • Control of the structure of tin sulfide thin films  
J-F. Pierson, R. Juliac, D. Pilloud, S. Migot, A. Tahir, J. Ghanbaja, B. Vigolo, N. Stein  
 Univ. Lorraine, CNRS, IJL - Nancy (FR)
- 11:35 DEPO3-O4-115 • Synthesis of metal doped diamond-like carbon films by magnetron sputtering  
L. Marcinauskas<sup>1,2</sup>, H. Zhairabany<sup>1</sup>, H. Khaksar<sup>3</sup>, M. Milieška<sup>2</sup>, A. Šarakovskis<sup>4</sup>, E. Vanags<sup>4</sup>  
<sup>1</sup> Department of Physics, Kaunas Univ. of Technology - Kaunas (LT)  
<sup>2</sup> Plasma Processing Laboratory, Lithuanian Energy Institute - Kaunas (LT)  
<sup>3</sup> Marian Smoluchowski Institute of Physics, Jagiellonian Univ. - Krakow (PL)  
<sup>4</sup> Institute of Solid State Physics, Univ. Latvia - Riga (LV)
- 11:55 DEPO3-O5-057 • The effect of ion potential energy on thin film crystallinity in pulsed filtered cathodic arc deposition  
D. Kalanov<sup>1</sup>, S. Mandazhiev<sup>1</sup>, J. Franze<sup>1</sup>, A. Anders<sup>1,2</sup>, Y. Unutulmazsoy<sup>1</sup>  
<sup>1</sup> Leibniz Institute of Surface Engineering (IOM) - Leipzig (DE)  
<sup>2</sup> Felix Bloch Institute of Solid State Physics, Leipzig Univ. - Leipzig (DE)

12:30

LUNCH



Wednesday 24 September

10:35 – 12:30

**MODIDD 2 Modelling, diagnostics and data-driven optimization of plasma processes**

ELLA FITZGERALD ROOM

 Chair: A. Lietz (US)

- 10:35 MODIDD2-O1-024 • Comparative analysis of ns- and ps-TALIF diagnostics of atomic oxygen generated with a plasma jet driven by a tailored voltage waveform  
Y. Song<sup>1</sup>, L. Invernizzi<sup>2</sup>, D. Stefas<sup>2</sup>, G. Lombardi<sup>2</sup>, K. Gazeli<sup>2</sup>, A. Nikiforov<sup>1</sup>, A. Sobota<sup>3</sup>, R. Morent<sup>1</sup>  
<sup>1</sup> Research Unit Plasma Tech; Fac. of Engineering and Architecture, Univ. Ghent (BE)  
<sup>2</sup> LSPM - CNRS, Univ. Sorbonne Paris Nord - Villetaneuse (FR)  
<sup>3</sup> EPGD Group, Dpt. Applied Physics and Science Education, Univ. Eindhoven (NL)
- 10:55 MODIDD2-O2-093 • Description of H-atom absolute densities and sub-ns decay times in a pulsed microtube plasma jet using ps-TALIF and a streak camera  
 Y. Agha, D. Stefas, L. Invernizzi, L. William, S. Prasanna, K. Gazeli, G. Lombardi  
LSPM - CNRS, Univ. Sorbonne Paris Nord - Villetaneuse (FR)
- 11:15 MODIDD2-O3-082 • Unraveling no production in N<sub>2</sub>-O<sub>2</sub> plasmas with 0D kinetic modeling and experimental validation  
T. Silva<sup>1</sup>, S. Bera<sup>2</sup>, C. Pintassilgo<sup>1,3</sup>, A. Herrmann<sup>2</sup>, S. Welzel<sup>2</sup>, M. Tsampas<sup>2</sup>, R. van de Sanden<sup>2</sup>, V. Guerra<sup>1</sup>  
<sup>1</sup> Inst. de Plasmas e Fusão Nuclear (IPFN), Inst. Superior Técnico, Univ. Lisboa (PT)  
<sup>2</sup> Dutch Institute for Fundamental Energy Research (DIFFER) - Eindhoven (NL)  
<sup>3</sup> Departamento de Engenharia Física, Faculdade de Engenharia, Univ. Porto (PT)
- 11:35 MODIDD2-O4-097 • Time-resolved bayesian analysis of low-pressure misty plasmas using a collisional-radiative model coupled to optical emission spectroscopy  
S. Chouteau<sup>1</sup>, A. Durocher-Jean<sup>2</sup>, M. Richard-Plouet<sup>3</sup>, A. Granier<sup>3</sup>, L. Stafford<sup>2</sup>  
<sup>1</sup> Univ. Osaka (JP)  
<sup>2</sup> Univ. Montréal, Québec (CA)  
<sup>3</sup> Institut des Matériaux Jean Rouxel de Nantes (FR)
- 11:55 MODIDD2-O5-099 • Transient behavior of charged particles in pulse-modulated inductively coupled Cl<sub>2</sub> discharge  
S. Kim, J.P. Booth, G. Curley  
Laboratoire de Physique des Plasmas - Palaiseau (FR)

12:30

LUNCH



Wednesday 24 September

**14:00 – 16:05**
**ANTIPOLIS AUDITORIUM**

Chair: T. Belmonte (FR)

**14:00 PLENARY TALK // Fundamental diagnostics and modeling for streamer discharge and its application for cancer treatment**
R. Ono
*Univ. Tokyo (JP)*
**AMELI 2 Plasma and/in liquid interaction**
**ANTIPOLIS AUDITORIUM**

Chair: T. Belmonte (FR)

**14:45 AMELI2-O1-055 • Reactive sputtering onto ionic liquid, a new process to synthesize compound nanoparticles**
A. Bousquet<sup>1</sup>, S. Ibrahim<sup>1</sup>, V. Ntomprougkidis<sup>1</sup>, J.M. Adanson<sup>1</sup>, P. Bonnet<sup>1</sup>, M. Richard-Plouet<sup>2</sup>, M. Le Granvalet<sup>2</sup>, S. Roth<sup>3</sup>, A. Bonduelle<sup>3</sup>
<sup>1</sup> ICCF - Clermont-Ferrand (FR)

<sup>2</sup> IMN - Nantes (FR)

<sup>3</sup> IFPEN - Solaize (FR)

**15:05 AMELI2-O2-058 • Sputtering of silver onto silicone oils: nanoparticle formation and mass transfer into the bulk solution**
F-E. Bol, S. Konstantinidis
*UMons - ChIPS - Mons (BE)*
**15:25 AMELI2-O3-030 • Formation of Ru catalytic nanoparticles onto polyethylene glycol by plasma sputtering**
A. Diop<sup>1</sup>, S. Atmane<sup>1</sup>, L. Gimenez<sup>1</sup>, J. Lemaire<sup>1</sup>, E. Millon<sup>1</sup>, S. Iseni<sup>1</sup>,

A. Sauldubois<sup>1,2</sup>, P. Andreatza<sup>3</sup>, A. Caillard<sup>1</sup>
<sup>1</sup> GREMI – CNRS, Univ. Orléans (FR)

<sup>2</sup> MACLE – CNRS - Orléans (FR)

<sup>3</sup> ICMN – CNRS, Univ. Orléans (FR)

**15:45 AMELI2-O4-080 • Deposition of ZnGa<sub>2</sub>O<sub>4</sub> thin films by reactive co-sputtering of liquid gallium**
J. Purans, M. Zubkins, E. Strods, E. Butanovs

*Institute of Solid State Physics, Univ. Latvia, Riga (LV)*
**16:05 COFFEE BREAK**
**16:35 POSTER SESSION #2 (UNTIL 18:30)**



Wednesday 24 September

14:00 – 16:05

**ITEC 1 Innovative applications,  
solutions and technologies**

ELLA FITZGERALD ROOM

 Chair: J. Alami (MA)

- 14:45 ITEC1-O1-048 ● Metal oxide reduction using inline openair-plasma process in combination with thin film deposition to enhance adhesion and improve durability in electronics  
D. Bensalem, M. Buske, Y. Hamedi, S. Kulkarni  
*Plasmatreat, Steinhagen (DE)*
- 15:05 ITEC1-O2-015 ● Pushing the limits of magnetron sputtering for innovative solutions  
E. Hays<sup>1</sup>, D. Muller<sup>1,2</sup>, C. Vandenabeele<sup>1,3</sup>, S. Lucas<sup>1</sup>  
<sup>1</sup>ICS - Innovative Coating Solutions - Gembloux (BE)  
<sup>2</sup>NCE, ULiège - Liège (BE)  
<sup>3</sup>LARN-NISM, UNamur - Namur (BE)
- 15:25 ITEC1-O3-006 ● Unravelling the mechanisms behind dislocation density reduction in tungsten-doped single-crystal diamond: a synchrotron X-ray investigation  
D. Nusimovici<sup>1,2</sup>, L. Valera<sup>1</sup>, T.N. Tran-Caliste<sup>3</sup>, J. Baruchel<sup>3</sup>, O. Mathon<sup>3</sup>, D. Eon<sup>4</sup>, D. Chaussende<sup>2</sup>, J. Bousquet<sup>1</sup>  
<sup>1</sup>DIAMFAB, Grenoble (FR)  
<sup>2</sup>Univ. Grenoble Alpes, CNRS, Grenoble INP, SIMaP, Grenoble (FR)  
<sup>3</sup>ESRF, Grenoble (FR)  
<sup>4</sup>Institut Néel, Grenoble (FR)
- 15:45 ITEC1-O4-139 ● Analysis and monitoring of protective coatings: advances in LECO's Glow Discharge Spectroscopy (GDS)  
A. Houel<sup>1</sup>, S. Bohm<sup>2</sup>, V. Dubujet<sup>1</sup>  
<sup>1</sup>LECO France (FR)  
<sup>2</sup>LECO Europe (FR)

16:05 COFFEE BREAK

16:35 POSTER SESSION #2 (UNTIL 18:30)



Thursday 25 September

**8:40 – 10:00**

ANTIPOLIS AUDITORIUM

 Chair: A. Granier (FR)

- 8:40 **PLENARY TALK // Plasma technologies advancing biomedicine and sustainability**  
**M. Bilek<sup>1,2</sup>, C. Tran<sup>1</sup>, A. Gilmour<sup>2</sup>, S. Cottam<sup>1</sup>, J. Sardharwalla<sup>2</sup>, S. Fraser<sup>2</sup>**  
<sup>1</sup> *School of Physics, Univ. Sydney (AU)*  
<sup>2</sup> *School of Biomedical Engineering, Univ. Sydney (AU)*

**DEPO 4 Plasma-assisted deposition,  
coatings and layers**

ANTIPOLIS AUDITORIUM

 Chair: A. Granier (FR)

- 9:25 DEPO4-O1-004 • Plasma deposition in non-equilibrium conditions  
D. Hegemann, P. Navascues  
*EMPA - St.Gallen (CH)*
- 9:45 DEPO4-O2-040 • Atmospheric-pressure Plasma Enhanced Chemical Vapor Deposition of size agents on glass fibers for glass-reinforced plastics  
M. Troia<sup>1</sup>, M. Haag<sup>2</sup>, C. Dobslaw<sup>3</sup>, D. Dobslaw<sup>4</sup>, A. Schulz<sup>1</sup>, M. Walker<sup>1</sup>,  
 D. Ben Salem<sup>5</sup>, P. Holste<sup>5</sup>, P. Delfs<sup>5</sup>, A. Knospe<sup>5</sup>, B. Glocker<sup>3</sup>  
<sup>1</sup> *IGVP, Univ. Stuttgart (DE)*  
<sup>2</sup> *ITA RWTH Aachen Univ. (DE)*  
<sup>3</sup> *PlasmaAir AG - Weil der Stadt (DE)*  
<sup>4</sup> *TTI GmbH - Stuttgart (DE)*  
<sup>5</sup> *PlasmaTreat GmbH - Steinhagen (DE)*

10:05

COFFEE BREAK



Thursday 25 September

8:40 – 10:00

**PSURF 3 Plasma surface processing**

ELLA FITZGERALD ROOM

 Chair: J-F. Pierson (FR)

9:25 PSURF3-O1-033 • In-situ XRD investigations during nitriding of duplex steel

D. Manova<sup>1</sup>, J. Bauer<sup>1</sup>, A. Dalke<sup>2,3</sup>, S. Mändl<sup>1</sup>

<sup>1</sup> *Leibniz Institute of Surface Engineering (IOM) - Leipzig (DE)*

<sup>2</sup> *Institute of Materials Engineering, Technische Univ. Bergakademie Freiberg - Freiberg (DE)*

<sup>3</sup> *ZeHS, Technische Univ. Bergakademie Freiberg - Freiberg (DE)*

9:45 PSURF3-O2-029 • Reduction of oxides using an Electron Cyclotron Wave Resonance Ar/H<sub>2</sub> plasma - towards H<sub>2</sub>O production on the Moon

M. Sikiric<sup>1,3</sup>, S. Bulou<sup>2</sup>, K. Hadler<sup>1,3</sup>, P. Choquet<sup>3</sup>

<sup>1</sup> *European Space Resources Innovation Centre, LIST, Esch-sur-Alzette (LU)*

<sup>2</sup> *Advanced Plasma & Vapor Deposition Processes Engineering, LIST, Esch-sur-Alzette (LU)*

<sup>3</sup> *Univ. Luxembourg - Faculty of Science, Technology and Medicine - Esch-sur-Alzette (LU)*

10:05

COFFEE BREAK



Thursday 25 September

**10:35 – 12:30**
**DEPO 5 Plasma-assisted deposition,  
coatings and layers**
**ANTIPOLIS AUDITORIUM**

Chair: M. Bilek (AU)

- 10:35 DEPO5-O1-092 • Plasma polymer thin films as adhesion primers in composite/elastomer assembly: controlling adhesion performance through deposition parameters  
M. Ezzehar, A. Airoudj, G. Schrodj, F. Bally-Le-Gall, V. Roucoules  
*Institut de Science des Matériaux de Mulhouse (IS2M), CNRS - Mulhouse (FR)*
- 10:55 DEPO5-O2-109 • Plasma polymer film as an interlayer to improve polymer-metal composites disassembly and recycling efficiency  
A. Culot<sup>1</sup>, R. Dantine<sup>1</sup>, S.A. Raut<sup>1</sup>, D. Cossement<sup>2</sup>, J.M. Raquez<sup>3</sup>, D. Thiry<sup>1</sup>  
<sup>1</sup> *Chimie des Interactions Plasma-Surface (ChIPS), Univ. Mons (BE)*  
<sup>2</sup> *Materia Nova Research Center, Parc Initialis, Mons (BE)*  
<sup>3</sup> *Service des Matériaux Polymères et Composites (SMPC), Univ. Mons (BE)*
- 11:15 DEPO5-O3-110 • Study of the chemical and textural properties of 2-vinylpyridine-based plasma polymers  
R. Costes<sup>1,2</sup>, A. Van der Lee<sup>1</sup>, S. Badaire<sup>2</sup>, A. Achille<sup>2</sup>, V. Rouessac<sup>1</sup>, S. Roualdes<sup>1</sup>  
<sup>1</sup> *Institut Européen des Membranes (IEM) - Montpellier (France)*  
<sup>2</sup> *Manufacture française des pneumatiques Michelin - Cébazat (France)*
- 11:35 DEPO5-O4-020 • Impact of surface chemistry on the morphology of plasma polymers  
P. Covin<sup>1</sup>, A. Airoudj<sup>1</sup>, C. Noël<sup>2</sup>, F. Bally-Le Gall<sup>1</sup>, T. Belmonte<sup>2</sup>, V. Roucoules<sup>1</sup>, J. Carneiro De Oliveira<sup>1</sup>  
<sup>1</sup> *Univ. Haute-Alsace, Univ. Strasbourg, CNRS, IS2M UMR 7361 - Mulhouse (FR)*  
<sup>2</sup> *Univ. Lorraine, CNRS, IJL - Nancy (FR)*
- 11:55 DEPO5-O5-039 • Formation of radicals in amine plasma polymer thin films and their potential for covalent binding of biomolecules  
L. Janu<sup>1</sup>, B. Beliančínová<sup>1</sup>, V.T. Santana<sup>2</sup>, P. Skládal<sup>3</sup>, L. Zajíčková<sup>1, 4</sup>  
<sup>1</sup> *Plasma Technologies, CEITEC, Univ. Brno (CZ)*  
<sup>2</sup> *Magneto-Optical and THz Spectroscopy, CEITEC, Univ. Brno (CZ)*  
<sup>3</sup> *Dpt. of Biochemistry, Faculty of Science, Masaryk Univ., Brno (CZ)*  
<sup>4</sup> *Dpt. of Condensed Matter Physics, Faculty of Science, Masaryk Univ., Brno (CZ)*

12:30

LUNCH



Thursday 25 September

**10:35 – 12:30**

**PSURF 4 Plasma surface processing**

**ELLA FITZGERALD ROOM**

 Chair: R. Dussart (FR)

- 10:35 PSURF4-O1-001 • Transient signals measurement capability for the analysis of thin films and surfaces reactivity  
P. Chapon, A. Stankova, L. Garrido  
*Horiba France - Palaiseau (FR)*
- 10:55 PSURF4-O2-105 • Plasma-surface characterization during V<sub>2</sub>O<sub>3</sub> thin films etching in SF<sub>6</sub>/Ar plasma  
T. Mbouja Signe, C. Mannequin, A. Girard, C. Cardinaud  
*Institut des Matériaux de Nantes Jean Rouxel (IMN) - Nantes (FR)*
- 11:15 PSURF4-O3-122 • Sensing enhancement of chemiresistive gas sensors by surface functionalization  
S. Kim  
*Inha Univ., Incheon (KR)*
- 11:35 PSURF4-O4-111 • Defect-engineered V<sub>2</sub>O<sub>5</sub>/TiO<sub>2</sub> thin films deposited by DC sputtering for improved carbofuran degradation  
D. Pjević, J. Georgijević, T. Stamenković, T. Vulić  
*Institute of Nuclear Sciences "VINCA", Univ. Belgrade (RS)*
- 11:55 PSURF4-O5-026 • Cleaning process of 3D and delicate heterogeneous structures with HDRF®, optimize chemistry with remote plasma, for microelectronics' and medical applications  
M. Segers, G. Terenziani, S. Benkoula  
*Plasma-Therm Europe - Grenoble (FR)*

12:30

LUNCH



Thursday 25 September

14:00 – 15:45

ANTIPOLIS AUDITORIUM

Chair: M. Richard-Plouet (Fr)

14:00 **PLENARY TALK // Tackling Lithium-ion battery challenges with PVD technologies**J. Alami*Mohammed VI Polytechnic Univ. (MA)***PSURF 5 Plasma surface processing**

ANTIPOLIS AUDITORIUM

Chair: M. Richard-Plouet (FR)

14:45 PSURF5-O1-007 • Enhancing corrosion resistance of magnesium alloys with plasma treatment and electrospun biodegradable polymer coatings

L. Zahedi, P. Ghourchi Beigi, M. Stupavská, D. Kovačik*Dpt. of Plasma Physics and Technology, CEPLANT, Faculty of Science, Masaryk Univ., Brno (CZ)*

15:05 PSURF5-O2-114 • Elucidating the growth mechanism of fonctionalized plasma polymer films using complex geometry substrates at various substrate temperatures

R. Dantinne, P. Leclere, D. Thiry*Univ. Mons (UMons) (BE)*

15:25 PSURF5-O3-124 • Plasma-induced physicochemical and topographical surface modifications for enhanced polymer adhesion

J-F. Coulon<sup>1, 2</sup>, D. Debarnot<sup>2</sup>, M. Yengui<sup>1</sup>, A. Al Khatib<sup>1</sup><sup>1</sup>*ECAM Louis de Broglie - Rennes (FR)*<sup>2</sup>*Institut des Molécules et Matériaux du Mans - Le Mans (FR)*

15:45

COFFEE BREAK



Thursday 25 September

14:00 – 15:45

**MODIDD 3 Modelling, diagnostics and data-driven optimization of plasma processes**

ELLA FITZGERALD ROOM

 Chair: C. Pintassilgo (PT)

- 14:45 MODIDD3-O1-113 • Understanding backscattered ions in HiPIMS plasmas  
Z. Belkaid, T. Minea, A. Revel  
*Laboratoire Physique des Gaz et Plasmas - Orsay (FR)*
- 15:05 MODIDD3-O2-054 • Enhancing energy flux to insulating surfaces using unipolar and bipolar HiPIMS pulse configurations  
 M. Farahani, T. Kozák, A. Dagmar Pajdarová, J. Čapek  
*Dpt. Physics & NTIS - European Centre of Excellence, Univ. West Bohemia, Pilsen (CZ)*
- 15:25 MODIDD3-O3-037 • Exploring ionized metal flux fraction in magnetron sputtering: insights from laboratory and industrial applications  
P. Vasina<sup>1</sup>, P. Klein<sup>1</sup>, M. Ondryas<sup>1</sup>, G. Lelovics<sup>1</sup>, V. Sochora<sup>2</sup>, M. Ucik<sup>3</sup>, J. Kluson<sup>3</sup>, M. Jilek<sup>3</sup>, A. Lümckemann<sup>4</sup>, J. Hnilica<sup>1</sup>  
<sup>1</sup> *Masaryk Univ. - Brno (CZ)*  
<sup>2</sup> *SHM - Sumpark (CZ)*  
<sup>3</sup> *Platit - Sumpark (CZ)*  
<sup>4</sup> *Platit - Selsach (CH)*

15:45

COFFEE BREAK



Thursday 25 September

**16:15 – 18:05**
**DEPO 6 Plasma-assisted deposition,  
coatings and layers**
**ANTIPOLIS AUDITORIUM**
 Chair: V. Jousseau (FR)

- 16:15 DEPO6-O1-042 • Hexagonal Boron Nitride deposition using micro-Plasma Enhanced Chemical Vapour Deposition ( $\mu$ PECVD) based on a Micro Hollow Cathode Discharge (MHCD)  
B. Menacer, K. Gazeli, C. Lazzaroni, V. Mille  
*CNRS LSPM - Villetaneuse (FR)*
- 16:35 DEPO6-O2-116 • Plasma-Enhanced Chemical Vapor Deposition of SiON optical thin films and nano-laminates  
S. Calvez, P. Dubreuil, A. Monmayrant, O. Gauthier-Lafaye  
*LAAS-CNRS - Toulouse (FR)*
- 16:55 DEPO6-O3-051 • Packaging solutions with plasma technology for enhancing gases barrier properties  
L. Coelho<sup>1</sup>, J. Rodeigues<sup>1</sup>, F. Loureiro<sup>1</sup>, M. Marques<sup>1</sup>, C. Ribeiro<sup>2</sup>, N. Pereira<sup>3</sup>, A. Rebola<sup>3</sup>  
<sup>1</sup> CeNTI - Centre of Nanotechnology and Advanced Materials - Vila Nova de Famalicão (PT)  
<sup>2</sup> TECMEAT - Agri-food Competence Center for the Meat sector - Vila Nova de Famalicão (PT)  
<sup>3</sup> UR - United Resins S.A. - Figueira da Foz (PT)
- 17:15 DEPO6-O4-120 • Atmospheric pressure plasma-assisted deposition of zinc-based coatings for agriculture applications  
 M. Roggio<sup>1, 2</sup>, M. Zabihzadeh Khajavi<sup>3, 4</sup>, A. Nikiforov<sup>3</sup>, F. Palumbo<sup>2</sup>, P. Favia<sup>1</sup>, N. De Geyter<sup>3</sup>  
<sup>1</sup> Univ. Bari Aldo Moro, Department of Chemistry - Bari (IT)  
<sup>2</sup> Institute of Nanotechnology National Research Council (CNR-NANOTEC) - Bari (IT)  
<sup>3</sup> Ghent Univ., Dpt. of Applied Physics, RUPT - Ghent (BE)  
<sup>4</sup> Ghent Univ., Dpt. of Food Technology, Safety and Health, RUFMFP - Ghent (BE)
- 17:35 DEPO6-O5-061 • TiO<sub>x</sub>C<sub>y</sub> organometallic multilayers for titanium dental implants: the role of carbon in promoting osseointegration  
S. Rubio, L. Houssiau  
*Univ. Namur (BE)*

**19:30 CONFERENCE DINNER COCKTAIL (UNTIL 22:30)**



Thursday 25 September

16:15 – 18:05

**MODIDD 4 Modelling, diagnostics and data-driven optimization of plasma processes**

ELLA FITZGERALD ROOM

Chair: T. Minea (FR)

16:15 MODIDD4-O1-021 • Diagnostic of DC arc plasmas in aeronautic arc fault conditions: application to detection

A. Hellé, R. Hugon, F. Brochard, G. Marcos  
*Institut Jean Lamour - Nancy (FR)*

16:35 MODIDD4-O2-088 • Plasma processing of monolayer graphene explored with numerical simulations

P. Vinchon<sup>1</sup>, N. Mauchamp<sup>1</sup>, L. Spiske<sup>1</sup>, Y. Miyamoto<sup>2</sup>, C. Bock<sup>3</sup>, S. Hamaguchi<sup>1</sup>  
<sup>1</sup> *Univ. Osaka (JP)* - <sup>2</sup> *National Institute of AIST, Tsukuba (JP)*  
<sup>3</sup> *Ruhr-Univ. - Bochum (DE)*

**NANO 1 Plasma nanotechnologies**

ELLA FITZGERALD ROOM

Chair: U. Cvelbar (SI)

16:55 NANO1-O1-028 • DC plasma-induced phase and morphological evolution of PtSn and PtRuSn nanoparticles produced in a magnetron-based gas aggregation source



A. Aryan<sup>1,2</sup>, A. Caillard<sup>1,3</sup>, M. Mikikian<sup>1</sup>, P. Andreatza<sup>2</sup>  
<sup>1</sup> *GREMI, Univ. Orléans (FR)* - <sup>2</sup> *ICMN, Univ. Orléans (FR)*  
<sup>3</sup> *UTOPII, AMU, CNAM, École Ponts ParisTec, INSA Lyon, Sorbonne Univ. (FR)*

17:15 NANO1-O2-076 • Thermally-induced microstructural evolution in nanoparticle-based CuO, WO<sub>3</sub> and CuO-WO<sub>3</sub> thin films for hydrogen gas sensing

J. Capek, K. Shaji, S. Haviar, P. Zeman, M. Procházka, R. Čerstvý, N. Kumar  
*Univ. West Bohemia, Pilsen (CZ)*

17:35 NANO1-O3-086 • Novel nanocomposite thin films by pulsed laser processes for plasmonic based sensing of cancer markers



M. Gireau<sup>1</sup>, F. Du<sup>2</sup>, J. Youssef<sup>3,4</sup>, S. Vergnole<sup>4</sup>, G. Humbert<sup>3</sup>, S. Zeng<sup>2</sup>,  
F. Dumas-Bouchiat<sup>1</sup>, C. Champeaux<sup>1</sup>  
<sup>1</sup> *Univ. Limoges, CNRS, IRCER, UMR 7315, Limoges (FR)*  
<sup>2</sup> *Univ. Troyes, CNRS, L2n, UMR 7076, Troyes (FR)*  
<sup>3</sup> *Univ. Limoges, CNRS, XLIM, UMR 7252, Limoges (FR)*  
<sup>4</sup> *ALPhANOV, Optics and Lasers Tech. Ctr., Inst. Optique d'Aquitaine - Limoges (FR)*

17:55 NANO1-O4-052 • Saturated plasmonic colours for identity security features obtained by magnetron sputtering and laser treatment

N. Jacquot<sup>1</sup>, W. Ravisy<sup>1</sup>, L. Dubost<sup>1</sup>, C. Hubert<sup>2</sup>, T. Girardin<sup>2</sup>,  
R. Mermillod-Blondin<sup>2</sup>, N. Destousches<sup>2</sup>  
<sup>1</sup> *IREIS, HEF Groupe, Andrézieux-Bouthéon (FR)*  
<sup>2</sup> *Laboratoire Hubert Curien, Univ. Jean Monnet, Saint-Étienne (FR)*

19:30 CONFERENCE DINNER COCKTAIL (UNTIL 22:30)



Friday 26 September

**8:40 – 10:05**
**ANTIPOLIS AUDITORIUM**
 Chair: R. Snyders (BE)

**8:40 PLENARY TALK // Plasma-catalyst interaction mechanisms for CO<sub>2</sub> recycling and molecule conversion**
O. Guaitella<sup>1</sup>, D. Sadi<sup>1</sup>, S. Bravo<sup>1</sup>, B. Berdugo<sup>1</sup>, M. Budde<sup>1</sup>, D. Pai<sup>1</sup>, T. Silva<sup>2</sup>, V. Guerra<sup>2</sup>
<sup>1</sup> LPP, CNRS, Sorbonne Univ., École Polytechnique, Institut Polytechnique de Paris, Palaiseau (FR)

<sup>2</sup> Instituto de Plasmas e Fusão Nuclear, Instituto Superior Técnico, Univ. Lisboa (PT)

**ITEC 2 Innovative applications, solutions and technologies**
**ANTIPOLIS AUDITORIUM**
 Chair: T. Silva (PT)

**9:25 ITEC2-O1-135 • Enhancing CO<sub>2</sub> plasma conversion by in-situ oxygen removal using a Solid Oxide Electrochemical Cell (SOEC)**
R. van de Sanden<sup>1</sup>, G.J. Zhang<sup>2</sup>, A. Pikalev<sup>1</sup>, X. Chen<sup>1</sup>
<sup>1</sup> Dutch Institute of Fundamental Energy Research, Eindhoven (NL)

<sup>2</sup> School of Electrical Engineering, Xi'an Jiaotong Univ. - Xi'an (CN)

**9:45 ITEC2-O2-034 • Exploring the potential of a pulsed thermionic vacuum arc as metal ion propulsion system**
C. Costin<sup>1</sup>, V. Tiron<sup>2</sup>, G. Andrisan<sup>1</sup>, I.L. Velicu<sup>1</sup>
<sup>1</sup> Faculty of Physics, Alexandru Ioan Cuza Univ. Iasi - Iasi (RO)

<sup>2</sup> Research Centre on Advanced Materials and Technologies, Dpt. Exact and Natural Science, Institute of Interdisciplinary Research, Alexandru Ioan Cuza Univ. Iasi - Iasi (RO)

10:05

COFFEE BREAK



Friday 26 September

8:40 – 10:05

**DEPO 7 Plasma-assisted deposition,  
coatings and layers**

ELLA FITZGERALD ROOM

 Chair: G. Henrion (FR)

- 9:25 DEPO7-O1-091 • Direct injection of iron acetate solutions in a low pressure plasma to prepare Fe<sub>2</sub>O<sub>3</sub>/TiO<sub>2</sub> nanocomposite thin films  
S. Hekking<sup>1,2</sup>, A. Goullet<sup>1</sup>, A. Granier<sup>1</sup>, C. Maheu<sup>1</sup>, L. Stafford<sup>2</sup>,  
M. Richard-Plouet<sup>1</sup>  
<sup>1</sup> *Nantes Univ., CNRS, Institut des Matériaux de Nantes Jean Rouxel, Nantes (FR)*  
<sup>2</sup> *Département de Physique, Univ. Montréal (CA)*
- 9:45 DEPO7-O2-106 • Aerosol assisted atmospheric pressure plasma deposition of hybrid TiO<sub>2</sub>-based photoactive nanocomposite coatings for water remediation  
R. Del Sole<sup>1</sup>, F. Palumbo<sup>2</sup>, C. Lo Porto<sup>3</sup>, R. Comparelli<sup>3</sup>, M.L. Curri<sup>1,3</sup>,  
F. Fracassi<sup>1,2</sup>, A. Milella<sup>1,2</sup>  
<sup>1</sup> *Univ. Bari Aldo Moro, Department of Chemistry - Bari (IT)*  
<sup>2</sup> *Istituto di Nanotecnologia, CNR - Bari (IT)*  
<sup>3</sup> *Istituto per i Processi Chimico-Fisici, CNR - Bari (IT)*

10:05

COFFEE BREAK



Friday 26 September

**10:35 – 12:10****ITEC 3 Innovative applications,  
solutions and technologies****ANTIPOLIS AUDITORIUM**
 Chair: S. Hamaguchi (JP)

- 10:35 **KEYNOTE // ITEC3-K1-125** • Study of CH<sub>4</sub> pyrolysis in a planar atmospheric gliding arc discharge  
R. Snyders  
*Univ. Mons (BE)*
- 11:05 ITEC3-O1-044 • Impact of swift heavy ions irradiation on the microstructural and electrochemical properties of sputtered vanadium nitride thin films for micro-supercapacitors  
J. Barbé<sup>1,2</sup>, A. Lebreton<sup>1,2</sup>, C. Douard<sup>1,2</sup>, C. Grygiel<sup>3</sup>, I. Monnet<sup>3</sup>, C. Lethien<sup>4,2</sup>, T. Brousse<sup>1,2</sup>  
<sup>1</sup> *Nantes Univ., CNRS, Institut des Matériaux de Nantes Jean Rouxel, IMN, Nantes (FR)*  
<sup>2</sup> *Réseau sur le Stockage Electrochimique de l'Energie (RS2E), CNRS FR 3459, Amiens (FR)*  
<sup>3</sup> *CIMAP, Normandie Univ., CEA, CNRS, UNICAEN, Caen (FR)*  
<sup>4</sup> *IEMN, Univ. Lille, CNRS, Univ. Polytechnique Hauts-de-France, UMR 8520 - IEMN, Lille (FR)*
- 11:25 ITEC3-O2-084 • Plasma thin films for high-frequency filtering supercapacitors  
U. Cvelbar, N.M. Santhosh  
*Jožef Stefan Institute - Ljubljana (SI)*
- 11:45 ITEC3-O3-078 • Lanthanum niobium oxide thin films deposited via reactive sputtering for high power micro-batteries  
O. Touré<sup>1, 2</sup>, J. Barbe<sup>1, 2, 3</sup>, M.P. Besland<sup>1</sup>, T. Brousse<sup>1, 2, 3</sup>  
<sup>1</sup> *Institut des Matériaux de Nantes Jean Rouxel, CNRS - Nantes (FR)*  
<sup>2</sup> *Nantes Univ. - Nantes (FR)*  
<sup>3</sup> *Réseau sur le Stockage Electrochimique de l'Energie (RS2E) - Amiens (FR)*
- 12:10 Closing ceremony

**ANTIPOLIS AUDITORIUM****14:00 SOCIAL PROGRAM**

For registered person / 2 activities proposed:

- Option #1 - Excursion to Grasse, international capital of Flowers and Perfume
- Option #2 - Walking tour on the coastal path "sentier de Tire-Poil"



Friday 26 September

10:35 – 12:10

**NANO 2 Plasma nanotechnologies**

ELLA FITZGERALD ROOM

 Chair: A. Bousquet (FR)

- 10:35 **KEYNOTE // NANO2-K1-010** • Optimisation and *in situ* control of the deposition of nanocomposite thin films in low pressure misty plasma  
A. Granier<sup>1</sup>, J. Chevet<sup>1</sup>, M. Feron<sup>2</sup>, R. Clergereaux<sup>3</sup>, P. Raynaud<sup>3</sup>, M. Kahn<sup>2</sup>, A. Goulet<sup>1</sup>, M. Richard-Plouet<sup>1</sup>  
<sup>1</sup> Nantes Univ., CNRS, Institut des Matériaux de Nantes Jean Rouxel, Nantes (FR)  
<sup>2</sup> Laboratoire de Chimie de Coordination UPR8241, CNRS, Toulouse (FR)  
<sup>3</sup> Laplace, Univ. Toulouse, CNRS, UPS, INPT, Toulouse (FR)
- 11:05 NANO2-O1-069 • Metal-doped DLC coating by PE-CVD coupled with pulsed liquid injection  
H. Klein<sup>1,2,3</sup>, L. Stafford<sup>3</sup>, R. Clergereaux<sup>2</sup>, M.L. Kahn<sup>2</sup>  
<sup>1</sup> CNRS-LCC - Toulouse (FR)  
<sup>2</sup> LAPLACE – Toulouse (FR)  
<sup>3</sup> Univ. Montréal (CA)
- 11:25 NANO2-O2-041 • Growth of gold-palladium nanoalloys by oblique angle deposition: exploration of their structure and optical properties  
M. Costes, J. Ramade, S. Rousselet, K. Dussailant, M. Marteau, F. Pailloux, S. Camelio, D. Babonneau  
Institut Pprime, CNRS, Univ. Poitiers, ISAE-ENSMA - Poitiers (FR)
- 11:45 NANO2-O3-018 • Oblique angle co-sputtering of nanostructured Ti-W thin films: influence of deposition current on structure and electrical properties  
H. Gerami, A. Besnard, J.M. Cote, N. Martin  
Femto-st institute - Besançon (FR)
- 12:10 Closing ceremony

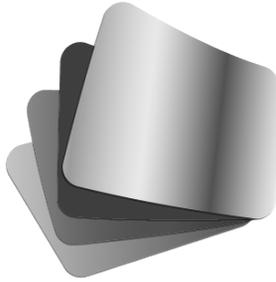
ANTIPOLIS AUDITORIUM

14:00 SOCIAL PROGRAM

For registered person / 2 activities proposed:

- Option #1 - Excursion to Grasse, international capital of Flowers and Perfume
- Option #2 - Walking tour on the coastal path “sentier de Tire-Poil”





# PLATHINIUM

PLASMA THIN FILM INTERNATIONAL UNION MEETING

## POSTER PROGRAM

- **P1 / Session #1**  
with exhibition cocktail  
Tuesday 23 September  
17:30 - 19:30
  - AMELI
  - DEPO
  - ITEC
  - MODIDD
- **P2 / Session #2**  
with refreshments  
Wednesday 24 September  
16:35 - 18:30
  - DEPO
  - GROM
  - MODIDD
  - NANO
  - PSURF



## Poster session #1

- AMELI Plasma and/in liquids interaction**
- AMELI-P1-053 Slow pulsed sputtering onto liquid: importance of surface refreshment and of plasma heating  
A. Caillard, S. Atmane, A. Diop, E. Millon, P. Brault  
*GREMI CNRS / Univ. Orléans (FR)*
- AMELI-P1-128 The influence of the discharge parameters on the physicochemical properties of plasma activated water  
L. Marcinauskas<sup>1</sup>, E. Jankaitytė<sup>2</sup>, M. Aikas<sup>1</sup>, L. Ragelienė<sup>2</sup>, R. Uscila<sup>1</sup>, A. Tamošiūnas<sup>1</sup>, Z. Naučienė<sup>2</sup>, V. Mildažienė<sup>2</sup>  
<sup>1</sup> *Plasma Processing Laboratory, Lithuanian Energy Institute - Kaunas (LT)*  
<sup>2</sup> *Faculty of Natural Sciences, Vytautas Magnus Univ. - Kaunas (LT)*
- AMELI-P1-146 Exfoliation and functionalization of graphite particles by pulsed plasma discharges in the gas-liquid phase  
A. Reguig, R. Chevigny, S. Cuynet, S. Fontana, C. Herold-Mareche, M. Ponçot, L. Adrien  
*Institut Jean Lamour, UMR 7198 CNRS – Univ. Lorraine - Nancy (FR)*
- AMELI-P1-147 Enhancement of grain quality of brewer's rice cultivar with plasma treatment of caryopsis using "Smart Agriculture System" based on collected data  
M. Hori, H. Hashizume  
*Nagoya Univ. - Nagoya (JP)*
- AMELI-P1-154 Optimizing ammonia decomposition for enhanced hydrogen production in a novel rotating gliding arc reactor  
M. Garcia Martinez<sup>1</sup>, S. Marin-Meana<sup>2</sup>, A. Megías-Sánchez<sup>2</sup>, M. Ruiz-Martin<sup>2</sup>, J. Cotrino<sup>2</sup>, A. González-Elipe<sup>2</sup>, M. Oliva-Ramírez<sup>3</sup>, A. Gómez-Ramírez<sup>3</sup>  
<sup>1</sup> *Univ. Cordoba (ES)*  
<sup>2</sup> *Instituto de Ciencia de Materiales de Sevilla (ES)*  
<sup>3</sup> *Univ. Sevilla (ES)*
- AMELI-P1-160 Liquid flow control in a dual-frequency APPJ on water solutions  
R. Fiorotto, E. Shakerinasab, M. Pierno, A. Patelli  
*Department of Physics and Astronomy "G. Galilei", Univ. Padova (IT)*
- AMELI-P1-170 Fixation of nitrogen in water with the use of a multiphase plasma reactor  
S. Mouchtouris<sup>1,2</sup>, A. Boudouvis<sup>1</sup>, E. Gogolides<sup>2</sup>, G. Kokkoris<sup>1</sup>  
<sup>1</sup> *School of Chemical Engineering, National Technical Univ. Athens (GR)*  
<sup>2</sup> *Nanoscience & Nanotechnology, National Centre of Scientific Research "Demokritos" - Athens (GR)*



Poster session #1

DEPO

Plasma-assisted deposition, coatings and layers

- DEPO-P1-013      Elaboration of 316L/Cu composite alloy using a hybrid PVD/SPS process  
Y. Pinot<sup>1</sup>, A. Besnard<sup>2</sup>, M.R. Ardigo-Besnard<sup>3</sup>, F. Bussiere<sup>3</sup>  
<sup>1</sup> *Arts et Métiers Institute of Technology, LaBoMaP - Cluny (FR)*  
<sup>2</sup> *Univ. Marie et Louis Pasteur, SUPMICROTECH, CNRS, Institut FEMTO-ST - Besançon (FR)*  
<sup>3</sup> *Laboratoire ICB, UMR 6303 CNRS, Univ. Bourgogne Europe - Dijon (FR)*
- DEPO-P1-027      Development and investigation of advanced coatings for high-temperature applications  
I. Toumi<sup>1</sup>, S. Achache<sup>1</sup>, A. Al Hussein<sup>1</sup>, B. Panicaud<sup>2</sup>  
<sup>1</sup> *ICD-LASMIS, UTT, UMR 6281, CNRS, Nogent (FR)*  
<sup>2</sup> *ICD-LASMIS, UTT, UMR 6281, CNRS, Troyes (FR)*
- DEPO-P1-050      Deposition of dielectric, and metal layer solution for TSV integration, innovative sequential process, application of low temperature deposition  
M. Segers, P.D. Szkutnik, S. Benkoula  
*Plasma-Therm Europe - Grenoble (FR)*
- DEPO-P1-068      Development of hydrogen barrier thin films based on silicon carbonitride  
M. Tetouani<sup>1</sup>, A. Al Hussein<sup>1</sup>, S. Achache<sup>1</sup>, M. Cherkaoui<sup>2</sup>  
<sup>1</sup> *UR LASMIS, Univ. Technologie de Troyes - Nogent (FR)*  
<sup>2</sup> *Univ. Ibn Tofail - Kenitra (MA)*
- DEPO-P1-072      Study of the impact of different dielectric materials on the performance and optical features of a Micro-Hollow Cathode Discharge (MHCD)  
N. Chazapis, B. Menacer, D. Stefas, G. Lombardi, C. Lazzaroni, K. Gazeli  
*LSPM - CNRS & Univ. Sorbonne Paris Nord,illetaneuse, Paris (FR)*
- DEPO-P1-140      On thermal stability and oxidation behavior of metastable W–Zr thin-film alloys  
M. Červená, J. Houška, R. Čerstvý, P. Zeman  
*Department of Physics and NTIS - European Centre of Excellence, Univ. West Bohemia, Pilsen (CZ)*
- DEPO-P1-148      Influence of substrate bias on the properties and conformality of TiN thin films deposited by High Power Impulse Magnetron Sputtering (HiPIMS)  
L. Seigneur<sup>1</sup>, J. Barbé<sup>1,2</sup>, M.P. Besland<sup>1</sup>  
<sup>1</sup> *Nantes Univ., CNRS, Institut des Matériaux de Nantes Jean Rouxel, Nantes (FR)*  
<sup>2</sup> *Réseau sur le Stockage Electrochimique de l'Energie (RS2E), CNRS FR 3459, Amiens (FR)*



## Poster session #1

- DEPO-P1-149 Plasma-grown vertically oriented graphene for supercapacitor electrodes  
A. Vesel, R. Zaplotnik, G. Primc  
*Jozef Stefan Institute - Ljubljana (SI)*
- DEPO-P1-158 Utilizing gas rarefaction to optimize preferential metal ion acceleration for epitaxial AlN growth on Silicon(111)  
N. Behravan<sup>1</sup>, T. Pitonakova<sup>2</sup>, T. Terzic<sup>3</sup>, A. Farhadizadeh<sup>1</sup>, M. Deluca<sup>4</sup>, M. Moridi<sup>4</sup>, D. Solonenko<sup>4</sup>, D. Lundin<sup>1</sup>  
<sup>1</sup> *Linköping Univ. - Linköping (SE)*  
<sup>2</sup> *Masaryk Univ. - Brno (CZ)*  
<sup>3</sup> *Otto-von-Guericke-Univ. Magdeburg - Magdeburg (DE)*  
<sup>4</sup> *Silicon Austria Labs GmbH - Villach (AT)*
- DEPO-P1-161 Aerosols as an innovating route for thin film deposition by PECVD  
R. Clergereaux<sup>1</sup>, P.A. Goutal<sup>1, 2, 3</sup>, M. Feron<sup>1, 4</sup>, P. Raynaud<sup>1</sup>, V. Rouessac<sup>2</sup>, S. Roualdes<sup>2</sup>, S. Devautour-Vinot<sup>3</sup>, M.L. Kahn<sup>4</sup>, J. Chevet<sup>5</sup>, A. Gouillet<sup>5</sup>, A. Granier<sup>5</sup>, M. Richard-Plouet<sup>5</sup>  
<sup>1</sup> *Laplace - Toulouse (FR)*  
<sup>2</sup> *IEM - Montpellier (FR)*  
<sup>3</sup> *ICGM - Montpellier (FR)*  
<sup>4</sup> *LCC - Toulouse (FR)*  
<sup>5</sup> *IMN - Nantes (FR)*
- DEPO-P1-162 Cu-substitution in lanthanum-deficient LaFeO<sub>3</sub> perovskites for enhanced photoelectrochemical solar hydrogen production  
T. Gries<sup>1</sup>, V. Guigoz<sup>1, 2</sup>, S. Migot<sup>1</sup>, S. Bruyère<sup>1</sup>, R. Schneider<sup>2</sup>  
<sup>1</sup> *Univ. Lorraine, CNRS, IJL - Nancy (FR)*  
<sup>2</sup> *Univ. Lorraine, CNRS, LRGP - Nancy (FR)*
- DEPO-P1-164 Deposition and characterisation of nitride thin films for data-driven optimisation of oxidation resistance  
L. Mereaux<sup>1</sup>, C. Jaoul<sup>1</sup>, E. Menou<sup>2</sup>, T. Vaubois<sup>2</sup>, M. Cavarroc<sup>2</sup>  
<sup>1</sup> *IRCER - Limoges (FR)*  
<sup>2</sup> *Safran Tech - Magny-Les-Hameaux (FR)*
- DEPO-P1-168 Fe:CH thin film deposition using an iron acetate solution in a Dielectric Barrier Discharge  
S. Hekking<sup>1, 2</sup>, A. Gouillet<sup>2</sup>, A. Granier<sup>2</sup>, C. Maheu<sup>2</sup>, M. Richard-Plouet<sup>2</sup>, L. Stafford<sup>1</sup>  
<sup>1</sup> *Département de Physique, Univ. Montréal (CA)*  
<sup>2</sup> *Nantes Univ., CNRS, Institut des Matériaux de Nantes Jean Rouxel (IMN) - Nantes (FR)*



Poster session #1

**ITEC**

**Innovative applications, solutions and technologies**

- ITEC-P1-062 Functionalized amorphous carbon coatings for low secondary electron yield and controlled surface resistance in particle accelerators  
W. Vollenberg<sup>1</sup>, P. Costa Pinto<sup>1</sup>, L. Mourier<sup>1</sup>, Y. Rabetsimalona<sup>1</sup>, N. Bundaleski<sup>2</sup>, I.M. Marrucho Ferreira<sup>2</sup>, J. Deuermeier<sup>2</sup>  
<sup>1</sup> CERN - Genève (CH)  
<sup>2</sup> Univ. Nova de Lisboa - Lisbon (PT)
- ITEC-P1-064 A low-temperature synthesis of strongly thermochromic VO<sub>2</sub>-based coatings for energy-saving smart windows  
M. Kaufman, E. M. Nia, J. Vlcek  
*Department of Physics and NTIS - European Centre of Excellence, Univ. West Bohemia, Pilsen (CZ)*
- ITEC-P1-085 Magnetron deposition of chromogenic thin films for smart windows  
J. Purans, M. Zubkins  
*Institute of Solid State Physics, Univ. Latvia - Riga (LT)*
- ITEC-P1-129 Transforming leak detection in vacuum environment with remote plasma optical emission spectroscopy  
B. Daniel, D. Monaghan  
*Genco Ltd - Liverpool (UK)*
- ITEC-P1-171 New QCM-Based diagnostic for quantitative time-resolved measurement of the ion flux in HiPIMS  
C. Ballage<sup>1</sup>, A. Kapran<sup>2</sup>, O. Vasilovici<sup>1</sup>, A. Bennacef<sup>3</sup>, T. Minea<sup>4</sup>  
<sup>1</sup> CNRS - LPGP - Orsay (FR)  
<sup>2</sup> CNRS - LPGP / FZU - Orsay (FR)  
<sup>3</sup> CNRS - LPGP / Sorbonne Univ. - Paris (FR)  
<sup>4</sup> Univ. Paris-Saclay - LPGP - Orsay (FR)

**MODIDD**

**Modelling, diagnostics and data-driven optimization of plasma processes**

- MODIDD-P1-036 Open-source modeling of gas phase dynamics in industrial magnetron sputtering processes  
J. Beyer, P. Nizenkov, S. Copplestone, A. Mirza  
*boltzplatz - numerical plasma dynamics GmbH - Stuttgart (DE)*
- MODIDD-P1-073 Rotational temperature measurements of N<sub>2</sub>(C), NO(A), and OH(A) in different micro hollow cathode discharge configurations using Optical Emission Spectroscopy  
D. Stefan<sup>1</sup>, G. Makrypodis<sup>2</sup>, B. Menacer<sup>1</sup>, P. Svarnas<sup>2</sup>, G. Lombardi<sup>1</sup>, C. Lazzaroni<sup>1</sup>, K. Gazeli<sup>1</sup>  
<sup>1</sup> LSPM - CNRS & Univ. Sorbonne Paris Nord - Villetaneuse (FR)  
<sup>2</sup> High Voltage Lab., Elec. & Computer Eng. Dpt., Univ. Patras, Rion (GR)



## Poster session #1

- MODIDD-P1-081 Assessing actinometry and line ratio techniques for species densities and electric field determination in DC glow discharges  
T. Silva<sup>1</sup>, L. Kuijpers<sup>2</sup>, E. Baratte<sup>3</sup>, V. Guerra<sup>1</sup>, R. Van De Sanden<sup>2</sup>, J.P. Booth<sup>3</sup>, O. Guaitella<sup>3</sup>  
<sup>1</sup> *Institute for Plasmas and Nuclear Fusion (IPFN) - Lisbon (PT)*  
<sup>2</sup> *Dutch Inst. for Fundamental Energy Research (DIFFER), Eindhoven (NL)*  
<sup>3</sup> *Laboratoire de Physique des Plasmas (LPP) - Paris (FR)*
- MODIDD-P1-094 Two dimensional distribution of atomic nitrogen absolute density in three DC MHCD  
K. Gazeli<sup>1</sup>, A. Remigy<sup>1</sup>, B. Menacer<sup>1</sup>, K. Kourtzanidis<sup>2</sup>, O. Gazeli<sup>3</sup>, G. Lombardi<sup>1</sup>, C. Lazzaroni<sup>1</sup>  
<sup>1</sup> *Univ. Sorbonne Paris Nord, LSPM, CNRS, UPR 3407 - Villetaneuse (FR)*  
<sup>2</sup> *CPERI, (CERTH, Thermi (GR)*  
<sup>3</sup> *FOSS Research Ctre for Sustainable Energy, Univ. Cyprus, Nicosia (CY)*
- MODIDD-P1-095 Analysis of sputtered species transport in High Power Impulse Magnetron Sputtering (HiPIMS) discharge employing magnetized QCM probe  
A. Kapran<sup>1</sup>, C. Ballage<sup>1</sup>, Z. Hubička<sup>2</sup>, T. Minea<sup>1</sup>  
<sup>1</sup> *LPGP, CNRS - Univ. Paris-Saclay - Orsay (FR)*  
<sup>2</sup> *FZU – Inst. of Physics of the Czech Academy of Sciences - Prague (CZ)*
- MODIDD-P1-101 Plasma-surface interactions in CO<sub>2</sub> glow discharges  
V. Guerra<sup>1</sup>, B. Berdugo<sup>2</sup>, A. Filipe<sup>1</sup>, O. Guaitella<sup>2</sup>, A.S. Morillo Candás<sup>2</sup>, P. Viegas<sup>1</sup>  
<sup>1</sup> *Instituto de Plasmas e Fusão Nuclear, Instituto Superior Técnico, Univ. Lisboa (PT)*  
<sup>2</sup> *LPP, CNRS, Sorbonne Univ., École Polytechnique, Institut Polytechnique de Paris - Palaiseau (FR)*
- MODIDD-P1-153 Study of the plasma pyrolysis of methane in a rotating gliding arc for carbon black synthesis  
N. Roy<sup>1</sup>, A. Panepinto<sup>2</sup>, T. Godfroid<sup>2</sup>, F. Mazeri<sup>2</sup>, A. Usoltseva<sup>3</sup>, V. Smits<sup>3</sup>, R. Snyders<sup>1,2</sup>  
<sup>1</sup> *Plasma-Surface Interaction Chemistry (ChIPS), Univ. Mons (BE)*  
<sup>2</sup> *Materia Nova Research Center, Mons (BE)*  
<sup>3</sup> *Innovation Centre, Phillips Carbon Black Limited, Ghislenghien (BE)*
- MODIDD-P1-157 Time-resolved measurements of secondary electron emission during ion bombardment  
S. Mändl<sup>1</sup>, H. Kersten<sup>2</sup>, D. Manova<sup>1</sup>  
<sup>1</sup> *Leibniz Institute of Surface Engineering (IOM) - Leipzig (DE)*  
<sup>2</sup> *Institut für Experimentelle und Angewandte Physik, Christian-Albrechts-Universität Kiel - Kiel (DE)*
- MODIDD-P1-167 Developing a modeling framework for plasma assisted solvolysis of fiber reinforced polymers  
G. Kokkoris<sup>1</sup>, A. Mouzakis<sup>1</sup>, D. Passaras<sup>1</sup>, D. Marinis<sup>2</sup>, E. Farsari<sup>2</sup>, S. Sfikas<sup>2</sup>, E. Amanatides<sup>2</sup>  
<sup>1</sup> *School of Chemical Engineering, National Technical Univ. Athens (GR)*  
<sup>2</sup> *Department of Chemical Engineering, Univ. Patras - Patras (GR)*



Poster session #2

DEPO

Plasma-assisted deposition, coatings and layers

- DEPO-P2-002      Influencing the properties of TiN and (Ti,Al)N hard coatings by modifying their composition and structural design  
D. Munteanu<sup>1</sup>, C. Lopes<sup>2</sup>, I. Borsan<sup>1</sup>, C. Gabor<sup>1</sup>, M.S. Rodrigues<sup>2</sup>, A. Ferreira<sup>2</sup>, F. Macedo<sup>2</sup>, E. Alves<sup>3</sup>, N.P. Barradas<sup>3</sup>, F. Vaz<sup>2</sup>  
<sup>1</sup> *Dept. of Material Science, Transilvania Univ. Brasov - Brasov (RO)*  
<sup>2</sup> *Physics Centre of Minho and Porto Univ. (CF-UM-UP), Univ. Minho - Braga (PT)*  
<sup>3</sup> *IPFN, Instituto de Plasmas e Fusão Nuclear, Instituto Superior Técnico, Univ. Lisboa - Lisbon (PT)*
- DEPO-P2-011      HEA thin films as protective barrier against carbon diffusion during SPS  
A. Besnard<sup>1</sup>, M. El Garah<sup>2</sup>, F. Sanchette<sup>2</sup>, Y. Pinot<sup>3</sup>, R. Charvet<sup>4</sup>, M.R. Ardigo-Besnard<sup>4</sup>, F. Herbst<sup>4</sup>, N. Geoffroy<sup>4</sup>  
<sup>1</sup> *Univ. Marie et Louis Pasteur, SUPMICROTECH, CNRS, Institut FEMTO-ST - Besançon (FR)*  
<sup>2</sup> *LASMIS, Antenne de Nogent et LRC CEA-LASMIS, NICCI, Nogent (FR)*  
<sup>3</sup> *Arts et Métiers Institute of Technology, LaBoMaP - Cluny (FR)*  
<sup>4</sup> *Laboratoire ICB, UMR 6303 CNRS, Univ. Bourgogne Europe - Dijon (FR)*
- DEPO-P2-014      Thermodynamic modeling and experimental investigation of Ti PVD coatings as protective barriers against carbon diffusion during SPS  
Y. Pinot<sup>1</sup>, R. Charvet<sup>2</sup>, M.R. Ardigo-Besnard<sup>2</sup>, F. Baras<sup>2</sup>, S. Le Gallet<sup>2</sup>, F. Herbst<sup>2</sup>, N. Geoffroy<sup>2</sup>, A. Besnard<sup>3</sup>  
<sup>1</sup> *Arts et Métiers Institute of Technology, LaBoMaP - Cluny (FR)*  
<sup>2</sup> *Laboratoire ICB, UMR 6303 CNRS, Univ. Bourgogne Europe - Dijon (FR)*  
<sup>3</sup> *Univ. Marie et Louis Pasteur, SUPMICROTECH, CNRS, Institut FEMTO-ST - Besançon (FR)*
- DEPO-P2-066      Nanostructuring of bismuth oxyfluoride thin films by oblique angle deposition for CO<sub>2</sub> photoconversion  
A.E. Kabouia<sup>1</sup>, A. Bousquet<sup>1</sup>, S. Roth<sup>2</sup>, A. Bonduelle<sup>2</sup>, M. Richard-Plouet<sup>3</sup>, M. Le Granvalet<sup>3</sup>, R. Smaali<sup>4</sup>, E. Centeno<sup>4</sup>  
<sup>1</sup> *Univ. Clermont Auvergne (UCA), ICCF - Clermont-Ferrand (FR)*  
<sup>2</sup> *IFP Energies nouvelles - Solaize (FR)*  
<sup>3</sup> *Nantes Univ., CNRS, Institut des Matériaux de Nantes Jean Rouxel (FR)*  
<sup>4</sup> *Univ. Clermont Auvergne, Clermont Auvergne INP, CNRS, Institut Pascal - Clermont-Ferrand (FR)*



## Poster session #2

- DEPO-P2-134 Discriminating between morphological and chemical effects on the antibacterial properties of metal thin films through laser surface structuring  
A-L. Thomann<sup>1</sup>, P. Bernal<sup>1</sup>, F. Brule-Morabito<sup>2</sup>, B. Aspe<sup>1</sup>, N. Semmar<sup>1</sup>, P. Andreazza<sup>3</sup>, E. Bourhis<sup>3</sup>, P. Brault<sup>1</sup>, M. Cavarroc<sup>4</sup>, A. Sauldubois<sup>1</sup>, T. Vaubois<sup>4</sup>, E. Menou<sup>4</sup>, A. Caillard<sup>1</sup>, C. Andreazza<sup>3</sup>  
<sup>1</sup> GREMI (CNRS / Univ. Orléans) - Orléans (FR)  
<sup>2</sup> ART ARNmessenger US55-INSERM / LI<sup>2</sup>RSO / Univ. Orléans, CHU d'Orléans - Orléans (FR)  
<sup>3</sup> ICMN (CNRS / Univ. Orléans) - Orléans (FR)  
<sup>4</sup> Safran Paris-Saclay – Safran Tech - Magny-les-Hameaux (FR)
- DEPO-P2-142 Nanostructure engineering and properties enhancement of Cu-based films by Zr and Ta alloying  
M. Zhadko, A. Benediktová, J. Houška, R. Čerstvý, P. Baroch, P. Zeman  
Univ. West Bohemia - Pilsen (CZ)
- DEPO-P2-151 Atomic Layer Deposition of ZnO on fullerene: comparing thermal and plasma-enhanced approaches towards a photoactive nanocomposite  
R. Del Sole<sup>1, 2</sup>, A. Milella<sup>1, 2</sup>, F. Fracassi<sup>1, 2</sup>, P. Parlanti<sup>3</sup>, M. Gemmi<sup>3</sup>, A.M. Coclite<sup>4, 5</sup>, F. Palumbo<sup>2</sup>  
<sup>1</sup> Univ. Bari Aldo Moro, Department of Chemistry - Bari (IT)  
<sup>2</sup> CNR-Institute of Nanotechnology - Bari (IT)  
<sup>3</sup> Center for Materials Interfaces, Electron Crystallography, Istituto Italiano di Tecnologia - Pontedera (IT)  
<sup>4</sup> Univ. Bari Aldo Moro, Department of Physics - Bari (IT)  
<sup>5</sup> Institute of Solid State Physics, NAWI Graz, Graz Univ. of Technology, - Graz (AT)
- DEPO-P2-159 Recyclable thin coatings deposited by mean of plasma-assisted techniques on polymer foils for food packaging applications  
F. Delfin<sup>1, 2</sup>, C. Forsich<sup>1</sup>, M. Schachinger<sup>1</sup>, S. Augl<sup>1</sup>, S. Brühl<sup>2</sup>, C. Burgstaller<sup>1</sup>, D. Heim<sup>1</sup>  
<sup>1</sup> Univ. Applied Sciences Upper Austria - Wels (AT)  
<sup>2</sup> Univ. Tecnológica Nacional, Facultad Regional Concepción del Uruguay - Concepción del Uruguay (AR)
- DEPO-P2-163 A new solution to remove macro-particles during reactive metal nitride arc Physical Vapour Deposition  
D. Monaghan<sup>1</sup>, P. Mccarthy<sup>1</sup>, V. Bellido<sup>1</sup>, T. Sgrilli<sup>1</sup>, C. Bamber<sup>2</sup>  
<sup>1</sup> Gencoa - Liverpool (UK)  
<sup>2</sup> Univ. Liverpool (UK)



Poster session #2

- DEPO-P2-173 Plasma deposition of III-V semiconductors: sputtering and RPVPE approaches  
K. Ouaras<sup>1</sup>, P. Roca I Cabarrocas<sup>1,2</sup>, L. Watrin<sup>1,2</sup>, L. Srinivasan<sup>1,2</sup>, A. Eurosi<sup>1,2</sup>, D. Meurice<sup>1</sup>  
<sup>1</sup>LPICM, CNRS, Ecole polytechnique, Institut Polytechnique de Paris, Palaiseau (FR)  
<sup>2</sup>Institut Photovoltaïque d'Ile-de-France (IPVF), Palaiseau (FR)
- GROM Thin films growth and modelling**
- GROM-P2-043 Influence of discharge parameters on the properties of TiO<sub>2</sub> films grown by reactive Bipolar HiPIMS discharges  
S. Debnarova<sup>1</sup>, M. Michiels<sup>1,2</sup>, S. Konstantinidis<sup>1</sup>  
<sup>1</sup>Plasma-Surface Interaction Chemistry, Univ. Mons, Mons (BE)  
<sup>2</sup>Haute École en Heinaut, Mons (BE)
- GROM-P2-127 Multisource deposition conditions prediction towards required composition of thin films  
J. Gutwirth<sup>1</sup>, T. Halenkovič<sup>1</sup>, S. Šlang<sup>1</sup>, V. Nazabal<sup>2,1</sup>, P. Němec<sup>1</sup>  
<sup>1</sup>Univ. Pardubice - Pardubice (CZ)  
<sup>2</sup>Univ. Rennes - Rennes (FR)
- MODIDD Modelling, diagnostics and data-driven optimization of plasma processes**
- MODIDD-P2-009 Pure ammonia microwave discharges: a global model  
T. Belmonte<sup>1</sup>, M.Y. Awaji<sup>1,2</sup>, L. Pentecoste<sup>1</sup>, C. Noel<sup>1</sup>, M. Belmahi<sup>1</sup>, T. Gries<sup>1</sup>  
<sup>1</sup>Univ. Lorraine, CNRS, IJL, Nancy (FR)  
<sup>2</sup>Department of Physical Sciences, Physics Division, College of Science, Jazan Univ., Jazan (SA)
- MODIDD-P2-017 Rate coefficients of the N + H + M(Ar, N<sub>2</sub>) → NH + M recombination reaction in flowing afterglows of microwave plasmas  
A. Ricard, V. Ferrer, J.P. Gardou, F. Marchal, J.P. Sarrette  
LAPLACE, Univ. Toulouse, CNRS, UPS, INPT, Toulouse (FR)
- MODIDD-P2-059 Experimental investigations on the impact of gas flow on the propagation dynamics of a pulsed-driven μm-scale plasma jet  
Y. Agha<sup>1</sup>, K. Giotis<sup>1,2</sup>, D. Stefan<sup>1</sup>, L. Invernizzi<sup>1</sup>, H. Hoefft<sup>3</sup>, P. Svarnas<sup>2</sup>, K. Gazeli<sup>1</sup>, G. Lombardi<sup>1</sup>  
<sup>1</sup>Univ. Sorbonne Paris Nord, LSPM, CNRS, UPR 3407, Villetaneuse (FR)  
<sup>2</sup>Univ. Patras, Electrical & Computer Engineering Dept., High Voltage Lab., Rion - Patras (GR)  
<sup>3</sup>Leibniz Inst. for Plasma Science and Technology (INP), Greifswald (DE)



## Poster session #2

- MODIDD-P2-098 Modelling N<sub>2</sub>-H<sub>2</sub> for ammonia production  
C. Pintassilgo<sup>1,2</sup>, S. Baghel<sup>1</sup>, M. Budde<sup>3</sup>, A. Gonçalves<sup>1</sup>,  
O. Guaitella<sup>3</sup>, L. Marques<sup>4</sup>, P. Pereira<sup>1</sup>, N. Pinhão<sup>1</sup>, L.L. Alves<sup>1</sup>  
<sup>1</sup> IPFN, Instituto de Plasmas e Fusão Nuclear - Lisboa (PT)  
<sup>2</sup> FEUP, Faculdade de Engenharia, Univ. Porto - Porto (PT)  
<sup>3</sup> LPP, Ecole Polytechnique - Palaiseau (FR)  
<sup>4</sup> Centro de Física da Univ. do Minho e do Porto - Braga (PT)
- MODIDD-P2-100 Ion energy distribution function measurement in hybrid HiPIMS  
with carbon target  
I. Naiko<sup>1,2</sup>, M. Čada<sup>1</sup>, A. Ostapenko<sup>1</sup>, Z. Hubička<sup>1</sup>  
<sup>1</sup> Institute of Physics, Academy of Sciences of the Czech Republic -  
Prague (CZ)  
<sup>2</sup> Charles Univ., Faculty of Mathematics and Physics, Dpt. Surface and  
Plasma Science - Prague (CZ)
- MODIDD-P2-126 Optimizing ECR plasma ashing for high yield during spintronic  
sensor fabrication on 200mm wafers  
F. Favita<sup>1</sup>, S. Cardoso<sup>1,2</sup>  
<sup>1</sup> INESC MN - Lisbon (PT)  
<sup>2</sup> Instituto Superior Técnico (IST) - Lisbon (PT)
- MODIDD-P2-137 Enhancing surface emission in micro-gap atmospheric discharge  
via harmonic excitation  
Y. Liu<sup>1</sup>, N. Le Thomas<sup>2,3</sup>, C. Leys<sup>1</sup>, A. Nikiforov<sup>1</sup>  
<sup>1</sup> RUPT, Dpt. Applied Physics, Faculty of Engineering and Architecture,  
Ghent Univ., Ghent (BE)  
<sup>2</sup> Photonics Research Group, INTEC Dpt., Ghent Univ. - IMEC, Ghent (BE)  
<sup>3</sup> Center for Nano- and Biophotonics, Ghent Univ., Ghent (BE)
- MODIDD-P2-156 Spectroscopy study of the LTE condition in the Laser Induced  
Breakdown used for the chlorine ion determination in building  
materials  
M. Garcia Martinez, J. Mateo Calvo, A. Rodero Serrano  
Univ. Cordoba (ES)
- MODIDD-P2-165 TIA plasma characterization by optical emission spectroscopy in  
the presence of a substrate  
B. Ganleu Monte<sup>1</sup>, C. Chazelas<sup>1</sup>, C. Dublanche-Tixier<sup>1</sup>, P. Tristant<sup>1</sup>,  
T. Belmonte<sup>2</sup>  
<sup>1</sup> Univ. Limoges, CNRS, IRCER, UMR 7315, Limoges (FR)  
<sup>2</sup> Univ. Lorraine, CNRS, IJL, UMR 7198, Nancy (FR)



Poster session #2

- MODIDD-P2-172 Line-specific radiation transport simulation in spatially non-uniform argon plasmas for self-consistent collisional-radiative modeling  
S. Chouteau<sup>1</sup>, H.C. Tsai<sup>2</sup>, Z. Donko<sup>3</sup>, T.V. Tsankov<sup>4</sup>, P. Hartmann<sup>3</sup>, J.S. Wu<sup>2</sup>, S. Hamaguchi<sup>5</sup>  
<sup>1</sup> *JSPS International Research Fellow P24751, Graduate School of Engineering, Univ. Osaka (JP)*  
<sup>2</sup> *Dpt. of Mechanical Engineering, National Yang Ming Chiao Tung Univ., Hsinchu, Taiwan (TW)*  
<sup>3</sup> *HUN-REN Wigner Research Centre for Physics, Budapest (HU)*  
<sup>4</sup> *LPP, CNRS, Ecole Polytechnique, Institut Polytechnique de Paris, Sorbonne Univ., Palaiseau (FR)*  
<sup>5</sup> *R<sup>3</sup> Institute of Newly-Emerging Science Design (INSD), Univ. Osaka (JP)*

**NANO Plasma nanotechnologies**

- NANO-P2-012 Photoluminescent ZnO-SiO<sub>2</sub> nanocomposites prepared by a hybrid process coupling aerosol and Plasma Enhanced Chemical Vapour Deposition  
M. Richard-Plouet<sup>1</sup>, J. Chevet<sup>1</sup>, M. Feron<sup>2,3</sup>, A. Granier<sup>1</sup>, M. Kahn<sup>3</sup>, R. Clergereaux<sup>2</sup>, A. Goullet<sup>1</sup>  
<sup>1</sup> *Nantes Univ., CNRS-IMN - Nantes (FR)*  
<sup>2</sup> *CNRS-Laplace - Toulouse (FR)*  
<sup>3</sup> *CNRS-LCC - Toulouse (FR)*
- NANO-P2-087 Pulsed laser sources for nanometer-scaled complex materials and devices  
M. Gireau<sup>1</sup>, F. Du<sup>2</sup>, J. Youssef<sup>3,4</sup>, S. Vergnole<sup>4</sup>, G. Humbert<sup>3</sup>, S. Zeng<sup>2</sup>, C. Champeaux<sup>1</sup>, F. Dumas-Bouchiat<sup>1</sup>  
<sup>1</sup> *Univ. Limoges, CNRS, IRCER, UMR 7315, Limoges (FR)*  
<sup>2</sup> *Univ. Troyes, CNRS, L2N, UMR 7076, Troyes (FR)*  
<sup>3</sup> *Univ. Limoges, CNRS, XLIM, UMR 7252, Limoges (FR)*  
<sup>4</sup> *ALPhANOV, Optics and Lasers Technology Ctr., Institut d'optique d'Aquitaine - Limoges (FR)*

**PSURF Plasma surface processing**

- PSURF-P2-032 Stability of expanded austenite during annealing in vacuum  
S. Mändl, D. Manova  
*Leibniz Institute of Surface Engineering (IOM) - Leipzig (DE)*
- PSURF-P2-074 Atomic Layer Etching of SiO<sub>2</sub> using CF<sub>4</sub> plasma in deposition regime at cryogenic temperature  
T. Tillocher<sup>1</sup>, M. Adjabi<sup>1</sup>, J. Nos<sup>1</sup>, S. Iseni<sup>1</sup>, G. Cunge<sup>2</sup>, M. Kogelschatz<sup>2</sup>, P. Lefauchaux<sup>1</sup>, L. Becerra<sup>1</sup>, E. Despiau-Pujo<sup>2</sup>, R. Dussart<sup>1</sup>  
<sup>1</sup> *GREMI – Univ. Orléans / CNRS - Orléans (FR)*  
<sup>2</sup> *LTM, Univ. Grenoble Alpes / CNRS / Grenoble INP / CEA Grenoble (FR)*



## Poster session #2

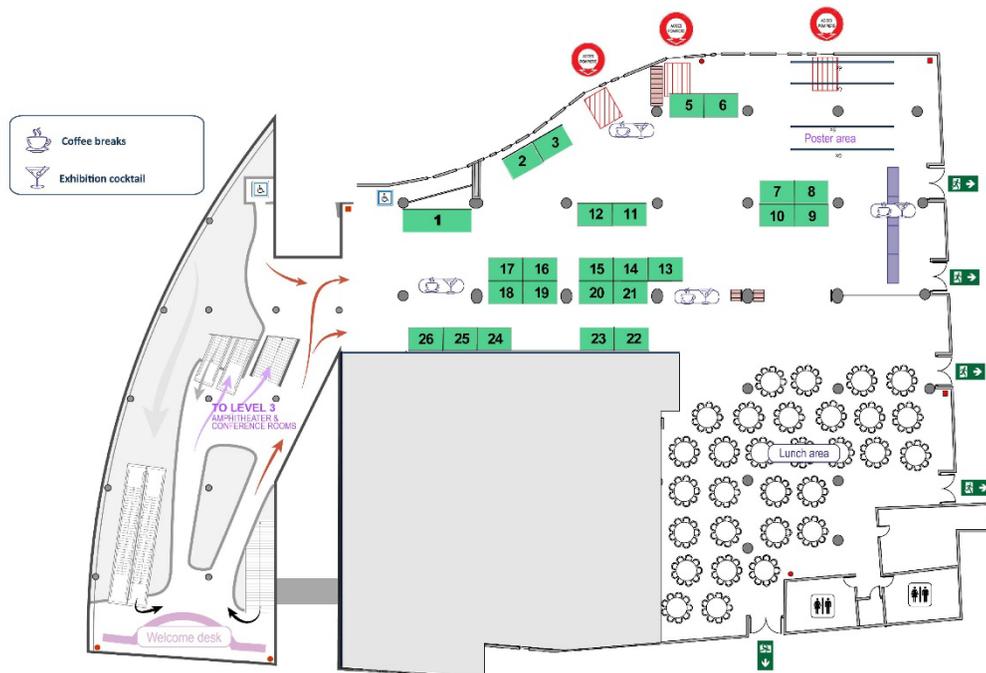
- PSURF-P2-079 Novel atmospheric-pressure plasma curing of anti-corrosion transparent silicon-based coating  
P. Ghourchi Beigi, L. Zahedi, R. Krumpolec, D. Kováčik  
*Dpt. Plasma Physics and Technology, CEPLANT, Faculty of Science, Masaryk Univ. - Brno (CZ)*
- PSURF-P2-133 Enhancing fiber/matrix interface in bio-based composites by cold plasma treatment: a step towards better fluid sealing  
F. Perrier-Michon<sup>1</sup>, S.A.E. Boyer<sup>2</sup>, A. Burr<sup>2</sup>, V. Rohani<sup>1</sup>  
<sup>1</sup> *PERSEE (MINES Paris PSL) - Sophia Antipolis (FR)*  
<sup>2</sup> *CEMEF CNRS 7635 (MINES Paris PSL) - Sophia Antipolis (FR)*
- PSURF-P2-144 Regulation of peripheral plasma characteristics via engineered alterations in electrode shielding materials under a direct current-biased power configuration  
C. Park<sup>1, 2</sup>, J. Cho<sup>3</sup>, G. Woo<sup>4</sup>  
<sup>1</sup> *Dpt. Semiconductor and Display Engineering, Sungkyunkwan Univ., Suwon (KR)*  
<sup>2</sup> *Samsung Electronics Semiconductor - Suwon (KR)*  
<sup>3</sup> *School of Mechanical Engineering, Sungkyunkwan Univ. - Suwon (KR)*  
<sup>4</sup> *SKKU Advanced Institute of Nanotechnology (SAINT), Sungkyunkwan Univ. - Suwon (KR)*
- PSURF-P2-150 Optimizing active screen plasma nitriding of AISI 316L through alternative approaches: reactor conditioning and argon addition  
A. Adami Vidal, R. Hugon, C. Noël, T. Czerwiec, G. Marcos  
*Univ. Lorraine, CNRS, Institut Jean Lamour - Nancy (FR)*
- PSURF-P2-166 Performance optimization of metallic bipolar plates for PEMFCs by post-discharge plasma  
L. Jacob<sup>1, 2</sup>, G. Marcos<sup>1</sup>, T. Gries<sup>1</sup>, M. Hautier<sup>2</sup>, T. Czerwiec<sup>1</sup>  
<sup>1</sup> *Univ. Lorraine - Institut Jean Lamour - Nancy (FR)*  
<sup>2</sup> *Symbio - Saint-Fons (FR)*
- PSURF-P2-169 Comparison between filamentary and diffuse dielectric barrier discharges at atmospheric pressure for the treatment of monolayer graphene films  
L. Stafford<sup>1</sup>, C. Moderie<sup>1</sup>, N. Naudé<sup>2</sup>, R. Martel<sup>1</sup>  
<sup>1</sup> *Univ. Montréal (CA)*  
<sup>2</sup> *LAPLACE – Univ. Toulouse (FR)*



# EXHIBITORS

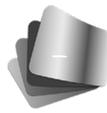
PLATINIUM  
PLASMA THIN FILM INTERNATIONAL UNION MEETING

## Exhibition map



## List of exhibitors

Company	booth	Company	booth
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CODEX INTERNATIONAL	22	PRO-VIDE	13
COMET	09	ROBEKO	19
HIDEN ANALYTICAL	05	SAIREM	10
INNODYS	17	SCIENTEC - PREVAC	08
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## ADVANCED ENERGY

### Stand # 15

Advanced Energy® (AE®) has dedicated over four decades to perfecting power enabling breakthrough design and driving growth for key clients in the semiconductor and industrial sectors. AE is a market leader in power supply, control solutions, and temperature measurement for critical processes such as etching, deposition, inspection, and implantation.

Through its platform architecture and innovative semiconductor manufacturing solutions, AE develops strategic partnerships, anticipates application needs, and swiftly designs products and solutions to meet specific requirements. Offering extensive capabilities and reliable performance, AE's system and integrated power solutions form the

foundation of the next generation of semiconductor manufacturing platforms. As a leader in DC and RF process power for 40 years, AE has been involved in chip fabrication in fabs worldwide. AE's expanded semiconductor portfolio now includes new power products as well as precise and reproducible sensor solutions to address customer needs in power and measurement.



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## ALLIANCE CONCEPT

### Stand # 12

Alliance Concept is an internationally renowned French manufacturer of high-end thin film deposition equipment by evaporation and magnetron sputtering. Alliance Concept also supplies turnkey helium and hydrogen tracer gas control machines as well as any other system requiring the implementation of vacuum technologies, such as ultra-vacuum degassing or surface activation by cold plasma.

Catalog or customized machines, Alliance Concept addresses its systems to scientific research laboratories but also to industrialists from all sectors: from the automotive industry to aeronautics, including semiconductors, photovoltaics, energy, medical, watchmaking and defense ...

With 34 years experience validated by hundreds of equipment in service, Alliance Concept knows how to innovate

to satisfy the most demanding requests of its customers.

Thanks to the machine park of its R & D laboratory, Alliance Concept offers its customers its knowledge to assist them in the development of innovative thin film deposition and leak testing processes. Alliance Concept is committed to providing a complete service, including technical and commercial needs, design, implementation and monitoring of equipment, all based on a rigorous ISO9001 certified management strategy.



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## CAMECA (AMETEK)

### Stand # 06

CAMECA is a world premier supplier of high-performance analytical instrumentation for R&D and process control of novel materials and advanced semiconductors. Our instruments measure elemental & isotopic composition down atomic resolution and equip the most prestigious government and university labs as well as leading high-tech industrial companies, supporting breakthrough research in materials and nanotechnologies, nuclear sciences, cell biology, environmental studies, and more. Our mission is to offer our customers the highest analytical performance in their specialized fields.

- The Invizo and LEAP 6000 Atom Probe Tomographs (APT) are state-of-the-art instruments for 3D compositional analysis at near atomic resolution. Applications include the compositional characterization of interfaces, grain boundaries, defects and dislocations, the detection of clusters and the study of precipitation-formation reactions.

- The IMS 7f-Auto, IMS Wf and SC Ultra, AKONIS and the new NanoSIMS-HR Secondary Ion Mass Spectrometers (SIMS) enable breakthrough research and development of metals, ceramics, semiconductors and novel energy materials, thanks to unparalleled performance in depth profiling (implants), trace element detection (contamination), diffusion/segregation in-situ characterization.

In 2024, CAMECA acquired Polygon Physics, reinforcing its leadership in ion and electron source technology.



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## CODEX INTERNATIONAL

### Stand # 22

#### Materials for Innovation and Research

For over 15 years, Codex International has been supporting the research community by supplying high-quality materials and substrates for thin film deposition. Our products are developed and tested using state-of-the-art technology. The rigor and responsiveness recognized by its customers make International Codex the reliable partner of labs and industries in France, Europe and the USA.



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## COMET

**Stand # 09**

Comet Plasma Control Technologies develops, manufactures and markets high-end radio frequency power components and systems solutions, such as RF Matching Networks, RF Generators and Vacuum Capacitors for the precise control of plasma applications that are necessary to manufacture advanced microchips.

Stop by at booth #09 to discover Synertia®, Comet's integrated RF Power Delivery platform that enables the unprecedented power delivery control required by plasma process tools for the next generation of microchips. Synertia® allows to manage the complexities of multi-layer next-generation memory and atomic-scale plasma processes. The unique, patented controls of Generator and Matching Network interact at highest possible speeds. These actionable insights enable more complex plasma applications than have ever been possible before.

**RF Power Generator Synertia® RFG**

Users fully control the unique performance accelerators of Synertia® RF generators, including:

- Multilevel pulsing that is tunable and highly configurable to deliver precise and repeatable control of the plasma.
- Consistent performance over millions of process steps.
- Advanced visualization of critical measurement and control parameters. This enables acceleration of process optimization and speeds time to solution. A wide variety of smart data sets for debugging, troubleshooting, and targeted analytics.

Higher yield is the result of Synertia®'s fast and agile process control, which delivers superior repeatability, faster tuning, and custom wave-shaping.

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## HIDEN ANALYTICAL

### Stand # 05

Hidden Analytical supply quadrupole mass spectrometers with high performance specifications and long-term reliability for research and process control.

Applications include gas analysis, catalysis, UHV surface science, SIMS and plasma research.

Hidden Analytical excels in creating bespoke instruments for thin film research. Our advanced devices, such as quadrupole mass spectrometers, plasma diagnostic tools, and gas analysers, lead the industry in precision and dependability. The Hidden EQP Series revolutionizes thin film processes with accurate plasma diagnostics, while the HPR-30 residual gas analyser enables real-time gas analysis for unmatched process control and quality.

We pride ourselves on delivering tailor-made solutions to meet individual client needs. Our committed team of scientists, engineers, and support specialists strive for superior customer satisfaction. Join prestigious research institutions and industries trusting Hidden Analytical to elevate their thin film research.



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[www.hiddenanalytical.com](http://www.hiddenanalytical.com)

## INNODYS

### Stand # 17

**INNODYS** is a European distributor of semiconductor systems and components. We offer our customers sales and after-sales service for the latest front-end processing tools, as well as components from the best American and European suppliers.

At the Plathinium trade show conference, we will represent **PORVAIR** (a wide range of high-purity porous media and reliable, highly efficient filtration products for gas and liquid applications) / **ASNA** (Inspiring the world with EXCELLENCE in intelligent sealing). **ASNA** offers a range of specialized materials to meet the rigorous requirements of the world's most sophisticated industries, including

semiconductors, pharmaceuticals, biotechnology, aerospace, and solar energy / **UE Precision Sensors** (pressure, flow, level, and temperature products for ultra-clean processing) / **OKYAYTECH** (atomic layer deposition and etching technology).



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## INNOVATIVE COATING SOLUTIONS (ICS)

### Stand # 18

ICS is your one-stop shop for efficient and optimized vacuum deposition processes. We specialize in the development of tailor-made thin films on complex 3D geometries and powder substrates, serving demanding sectors from energy storage to optics, defense, and beyond. Our engineering team also designs and builds advanced hardware, including custom coaters, high-rate metallic lithium sources (up to 20  $\mu\text{m}/\text{min}$ ), and plasma regulation systems tailored to industrial needs. ICS provides flexible coating services, process development, and on-site technology transfer to accelerate product qualification and industrial scale-up. In parallel, ICS develops proprietary digital tools to streamline R&D workflows. Virtual Coater™ simulates PVD processes, predicting thin-film growth and properties to reduce costly trial-and-error. Optima™ applies genetic algorithms to optimize multilayer coatings

for targeted optical and functional performance. With more than 35 years of combined expertise in thin-film technology, our team ensures the highest standards of quality and reliability. ICS supports innovation from lab to factory with a fast-growing client base across Europe, North America, and Asia. We are proud sponsors of Plathinium 2025 and invite you to meet us to explore how ICS can help you push the boundaries of functional coatings and accelerate your next innovation.



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## IONAUTICS AB

### Stand # 20

Ionautics is the leading provider of High-Power Impulse Magnetron Sputtering (HiPIMS) technology and process know-how. With extensive expertise and high-quality products, Ionautics provide new solutions for advanced materials through the HiPIMS technology. Our products offer complete process control allowing reliable, robust, and high-quality thin films with accurate reproducibility.



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## KENOSISTEC SRL

### Stand # 11

Kenosistec is dedicated to transforming industries with state-of-the-art equipment, including physical vapor deposition (PVD), Plasma-Enhanced Chemical Vapor Deposition (PECVD), Plasma Etching, Pulsed Laser Deposition (PLD) and more. Our precision-crafted machines redefine manufacturing standards, offering unparalleled efficiency and reliability.

Established in 2005, Kenosistec is a pioneering force headquartered in Casarile, near Milan (Italy), leading

innovation in the realm of High Vacuum Coatings and Plasma technology. We proudly stand as an ISO 9001-certified manufacturer specializing in advanced equipment for plant production.



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[www.kenosistec.com](http://www.kenosistec.com)

## LECO FRANCE

### Stand # 23

#### LECO – Analytical Innovation for Laboratory and Production Environments

**LECO is a global leader in elemental analysis.** We offer advanced solutions for material characterization, including coatings, thin films, and surface treatments.

Our Glow Discharge Spectroscopy (**GDS**) technology enables rapid depth profiling and bulk elemental analysis of metallic, multilayer, and conductive coatings. It is ideal for quality control, corrosion protection validation, and plasma-assisted deposition studies.

**CS** and **ONH** instruments provide precise quantification of carbon, sulfur, oxygen, nitrogen, and hydrogen—critical elements in metallic materials and protective layers.

Our **metallography** expertise relies on tools for sample preparation and visual evaluation, complemented by mechanical tests such as hardness measurement.

Beyond surface-focused technologies, LECO also offers comprehensive solutions in elemental analysis (C, H, N, S, O, TOC), thermogravimetric analysis, and **GC-TOF/GCxGC-TOF** chromatography, supporting both organic and inorganic matrices, solids and liquids.

We support our clients with personalized services: consulting, training, technical support, and after-sales service—ensuring seamless integration into laboratories and industrial environments.



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## NEYCO – HEF GROUP

### Stand # 01

Neyco is the French specialist in the vacuum/ultra-vacuum and inorganic materials markets. With 70 years of cutting-edge expertise and a rigorous commitment to improvement, our ability to advise and our adaptability are strengthened.

Above all, Neyco is a team of experts with a spirit of initiative, focused on people and the quality of relationships, concerned about the well-being and fulfilment of their colleagues and partners.

Neyco stands for quality and expertise in inorganic materials, thin film deposition, microscopy, vacuum and ultra-high vacuum.

Working hand in hand with industry and research laboratories, it is this diversity that enables us to be at the cutting edge of top-of-the-range technologies, and to

provide 'standard' or 'custom' solutions for technical products; in the same way as consultancy: Neyco is a bridge between Research and Industry.

Well-being in the workplace is vital for individual fulfilment, and the same goes for our partners. This is what motivates our employees every day to bring their expertise and rigour to bear in order to satisfy the requests they receive in the best possible way - whatever they may be.

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## OMEGA PHYSICS

### Stand # 02

Omega Physics offers customized solutions for vacuum, materials synthesis and cryogenics: engineered vacuum chambers, adapted pumping systems, PVD and CVD turnkey reactors...

Moreover, we distribute high quality brands (Kashiyama, Inficon, Shimadzu) and a wide range of standard vacuum fittings.



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## OMICRON TECHNOLOGIES

### Stand # 15

Since 1988, OMICRON Technologies is serving Science and Industries using high purity fluids, vacuum and ultra-high vacuum, temperature, power and plasmas. As a distributor of many renowned brands in these fields, working in close collaboration as partners, we are together able to provide best advice and support in a product selection, perfectly matching any application constraint.

Our engineering service complements this comprehensive offering by the design and manufacture of custom systems (gas mixers, diluters, humidifiers, liquid

vaporizers or test benches either for industry or research labs) with a constant focus on performance, innovation, and ease of use combination.



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## PLASMA-THERM

### Stand # 24

Plasma-Therm is a global manufacturer of advanced plasma processing equipment. Its tools and processes are used to support manufacturing needs in etch, deposition, rapid thermal processing, and plasma dicing technologies. The company serves the semiconductor and compound semiconductor industries in developing solutions for the wireless, power device, MEMS, photonics, advanced packaging, and data storage markets. With locations in North America, Europe, and Asia-

Pacific, Plasma-Therm meets the diverse needs of its customers with exceptional customer service.



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## POLYTEC FRANCE

### Stand # 26

The Polytec group has a worldwide presence through its subsidiaries and representatives. As a manufacturer and specialist, Polytec designs optical measurement equipment for real-time non-destructive testing: vibrometry, velocimetry, surface metrology and on-line spectrometry.

Also a distributor, Polytec offers complementary product ranges in photonics, vision, industrial process, etc. Polytec France supports all professionals in the public sector (Education, Research) and industry (Aeronautics, Automotive, Defence, Electronics, Food, Biomedical, Agriculture, Cosmetics, etc.). Based in Chatillon (92), the French

subsidiary operates throughout France and offers its customers a wide range of alternatives in addition to a high-quality technical and after-sales service: sales, rental, measurement services, training, etc.



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## PRO-VIDE

### Stand # 13

#### Pro-Vide – Customized Solutions for Vacuum and Ultra-High Vacuum

Pro-Vide is a French designer and manufacturer with more than 50 years of expertise. We support our clients from needs analysis through to after-sales service, with a strong focus on performance and reliability.

With our design office, we create original technical solutions for vacuum and ultra-high vacuum environments. Our machining and metalworking workshop allows us to produce in-house:

- Vacuum chambers, components, viewports, ceramic/metal feedthroughs,
  - Sample holders, manipulators, deposition sources, plasma systems, ovens...
- Our experienced teams also provide a complete range of services:
- Maintenance, troubleshooting, machining of hard materials (ceramics, glass, sapphire),

- 5-axis waterjet cutting, stainless steel fabrication, laser/TIG welding...

In addition, we are an authorized distributor of vacuum equipment (pumps, cryogenerators, oils, RF/DC generators, gauges, fittings, etc.).

We are also official partners of **Kashiyama** and **Shimadzu**, renowned for their reliable and high-performance vacuum pumps.



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## ROBEKO

### Stand # 19

robeko is a supplier of components and materials as well as a technology partner for sputter deposition. We are European distributor for the cutting-edge products of our partners Sputtering Components, Ionautics, House of Plasma, Sairem, ICS, RF Industries, PLASUS, Magpuls and TFC GmbH. robeko provides planar and rotatable sputtering targets and bonding services for tribological, decorative and optical applications. We are proud of our in house manufacturing capabilities for cast planar targets and planar target

bonding. As a technology partner our capabilities are ranging from feasibility studies and layer development to upscaling and process transfer into industrial production.



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## SAIREM

### Stand # 10

For more than 45 years, SAIREM has been designing innovative solutions for industry using microwave and RF technology: generators, high-performance industrial machines, and related services. The company offers one of the most advanced ranges for thermal processing and plasma generation. SAIREM has developed a **patented solution combining solid-state microwave generators and advanced plasma sources**, capable of producing very high-density plasmas. These systems support a wide range of cutting-edge applications, including diamond synthesis by chemical vapor deposition (CVD), etching, PE-CVD, PE-ALD, and PE-ALE.

Among these innovations, the **PlasmaVac source** features a self-matching architecture that prevents power loss and enables matching across a wide range of operating conditions—without requiring an external impedance matching system. The second, a collisional-type source, enables processes requiring a high concentration of reactive species, such as high-rate

PECVD or isotropic etching, with stable operation at pressures ranging from 1 to several tens of pascals.

SAIREM's **2540 MHz solid-state generators** deliver stable and precise microwave power, with continuous wave and pulsed modes. Their design ensures a long service life, excellent frequency stability, and safe operation without high voltage—making them particularly suitable for demanding plasma processes where reliability and fine control are essential.

Through its portfolio of patented technologies and commitment to innovation, SAIREM continues to lead the way in industrial microwave and plasma processing.



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## SCIENTEC - PREVAC

### Stand # 8

ScienTec is one of the largest distributors within the French market, specializing in the distribution of surface analysis technologies that span from nanometer to millimeter scales, catering to both research and industrial sectors.

ScienTec is the representative of Prevac that manufacture Vacuum systems for analysis & deposition (PVD-PLD-MBE). Furthermore, ScienTec presents a wide-ranging selection of scientific equipment options, including:

- AFM microscopes: Best price / performance AFM (High resolution, ResiScope, HD-KFM, sMIM, multiple environments)
- SEM microscopes: Superior price-to-performance tabletop and standard SEM (robustness, ease-of-use, EDS analysis)

- IR and RAMAN spectroscopies: submicron scale, better than ATR
- Nanoindentors: Hardness, scratch, Young modulus, ambient/vacuum environments
- Optical and mechanical profilometers: single & automated measurements
- Vacuum systems for analysis & deposition (PVD – PLD – MBE)
- Thin film analyzers: Single-spot, microscopic-spot thickness or automated.


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## SINDLHAUSER MATERIALS

### Stand # 03

Sindlhauser Materials GmbH is an internationally active company that specializes in the manufacture and sale of materials and components for PVD coating processes. The product range includes sputtering targets, oxide and non-oxide ceramics, LaB<sub>6</sub> cathodes, suspensions, granulates, evaporation materials and components made of tungsten, tantalum and molybdenum. The portfolio also includes specialized oils and lubricants for vacuum pumps. In addition to manufacturing, Sindlhauser Materials also offers services such as consulting, product development, target bonding and recycling.

Sindlhauser prioritizes sustainability and resource efficiency, implementing a comprehensive take-back and recycling program to recover valuable materials. Research and development play an important role. For example, the company has developed innovative

products such as the high-performance absorber PeroLab® and high-purity Ru-targets as a cost-effective alternative to Au.

The company supplies demanding industries worldwide such as semiconductor production, glass, packaging and decoration, sensor technology, optics, lighting technology and manufacturers for applications in the fields of medical technology, autonomous systems and modern display technologies.

Our team is eager to exchange ideas with you and committed to delivering expert advice and reliable support.


**SINDLHAUSER**  
**MATERIALS** ®

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## SOLCERA

### Stand # 21

#### **Solcera: Expertise in advanced ceramics for vacuum and ultra-high vacuum**

With a 200-year heritage in advanced ceramics and more than 50 years of experience in brazed hermetic assemblies, Solcera is a leader in solutions for vacuum and ultra-high vacuum applications. Its technical ceramics, ceramic-to-metal and glass-metal assemblies guarantee high-level of sealing, essential for demanding environments such as aerospace, nuclear, scientific research and particle accelerators.

Solcera operates from two sites in France and is strengthening its international presence through subsidiaries in Brazil

and Germany and a sales office in Spain. In close collaboration with its customers, Solcera develops customized solutions, from prototyping to volume production, thanks to recognized expertise and a capacity for constant innovation.



**SOLCERA**  
Advanced Materials

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## SPM AG

### Stand # 07

SPM delivers comprehensive semiconductor solutions that enhance your production efficiency through specialized sputtering target bonding services, high-quality spare parts, and technical support. Your manufacturing benefits from reduced costs, improved yields, and lower total cost of ownership through established partnerships with leading global material manufacturers. With facilities in Liechtenstein and Croatia since 2018, SPM ensures reliable delivery times across Europe. The Croatian operation provides import, storage, and distribution services alongside bonding capabilities, offering complete support for EU manufacturers. The proprietary bonding technology, developed in Japan, features a unique pre-wetting technique that works completely material-independent without requiring metallization. This ensures consistent, stable quality for your

production needs. Every process is fully customized—from material selection through bonding and backing plate specifications—tailored to your unique requirements.

Continuous innovation introduces new materials and solutions that optimize your production processes. Through close collaboration between suppliers and manufacturers, SPM delivers measurable results that strengthen your competitive position in the semiconductor market while addressing your specific manufacturing challenges.



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## SURCOTEC

### Stand # 14

**Surcotec SA**, founded in 1995 in Plan-les-Ouates (Geneva, Switzerland), is a specialist in vacuum coating and surface engineering. With strong expertise in PVD, PECVD, and ALD technologies, the company develops coatings that combine aesthetics and performance for a wide range of demanding applications. One of its key markets is Swiss watchmaking, where Surcotec delivers decorative and protective layers that enhance durability, color stability, and the luxury finish of timepieces. Beyond horology, the company serves multiple industries including micro-engineering, optics, medical devices, and aerospace. This versatility highlights Surcotec's ability to adapt advanced coating technologies to very diverse technical and design requirements.

Its offer covers the entire value chain: from surface preparation and coating deposition to industrial analysis and system design. Surcotec also invests in

large-scale capabilities, such as Surcoflex, a roll-to-roll vacuum coating unit launched in 2016 to address high-volume and flexible manufacturing needs.

In addition, the company provides analytical services, including SEM-EDX microscopy and contaminant testing, supporting quality assurance and industrial safety. By combining cutting-edge surface engineering with cross-sector expertise, Surcotec has built a solid reputation as a reliable Swiss partner for innovation, precision, and long-term collaboration.

**SURCOTEC**   
SURFACE COATING TECHNOLOGY

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## TESTBOURNE BV

### Stand # 25

Testbourne is a leading supplier of materials and instruments for Industries and Research & Development. we have over 45 years of experience with metals, alloys and compounds.

Testbourne supplies an extensive selection of materials available in fabricated forms including sputtering/arc targets, evaporation materials, powders, wire, rods & sheets.

For your evaporation requirement we also supply evaporation sources, multi-strand filaments, wire baskets, boats and crucibles.

We supply our materials in a variety of markets, including:

- Glass Coatings: Providing advanced materials for innovative glass coating technologies.
- Decorative & Hard-Wearing Coatings: Enabling the production of aesthetically pleasing and durable coatings.
- Electronics: Supplying critical materials for electronic components and devices.

- Energy: Supporting sustainable energy solutions with high-performance materials.
- Defence: Offering specialised materials for high-stakes defense applications.
- Semiconductors: Supplying precision materials crucial for semiconductor manufacturing.
- Government Research Establishments & Universities: Partnering with academic and research institutions to drive scientific advancements.

Testbourne is more than a supplier – we are your trusted partner in material science solutions. Our expertise, commitment to quality and dedication to customer success set us apart.



**Testbourne**

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## VAT

### Stand # 16

We change the world with vacuum solutions – that is our purpose as the world's leading supplier of high-end vacuum valves. The Group reports in two segments: Valves and Global Service. The Valves segment is a global developer, manufacturer and supplier of vacuum valves for the semiconductor, displays, photovoltaics and vacuum coating industries as well as for the industrial and research sector. Global Service provides local expert support to customers and offers genuine spare parts,

repairs and upgrades. In 2024, VAT employs some 3,200 people worldwide, with representatives in 29 countries and manufacturing sites in Switzerland, Malaysia, and Romania.



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# PLATHINIUM

PLASMA THIN FILM INTERNATIONAL UNION MEETING

See you for the 5<sup>th</sup> edition

20 - 24 September 2027

Antibes, French Riviera

[www.plathinium.com](http://www.plathinium.com)

# LECO

EMPOWERING RESULTS

## LECO – Empowering Your Results in Surface and Material Analysis

LECO delivers advanced solutions for surface and material characterization, supporting industries such as microelectronics, energy, aerospace, and more

- Glow Discharge Spectroscopy (GDS) for fast depth profiling and bulk analysis of metallic and multilayer coatings
- Metallography tools for thin film evaluation, microstructure analysis, and hardness testing
- Elemental analysis (C, H, N, S, O, TOC) for both organic and inorganic matrices, solids and liquids

From lab to production, LECO empowers your results with precision instrumentation and expert support: consulting, training, and technical service tailored to your needs.



GDS series



CS series



SX series



Let's keep in touch !

# Overview program

Monday 22 Sept.		Tuesday 23 Sept.		Wednesday 24 Sept.		Thursday 25 Sept.		Friday 26 Sept.	
Antipolis Auditorium		Antipolis Auditorium		Antipolis Auditorium		Antipolis Auditorium		Antipolis Auditorium	
Ella Fitzgerald Room		Ella Fitzgerald Room		Ella Fitzgerald Room		Ella Fitzgerald Room		Ella Fitzgerald Room	
8:30 - 9:10	Short course Registration Badge pick up	Registration Badge pick up	Registration Badge pick up						
9:10 - 9:25		Opening ceremony							
9:25 - 10:05	9:00 - 10:40 Tutorial #1 <i>T. Belmonte</i>	<b>PL1 / M. SANKARAN</b>	<b>PL3 / A. LIETZ</b>					<b>PL5 / M. BILEK</b>	<b>PL7 / O. GUATELLA</b>
10:05 - 10:35		Coffee break 30'	Coffee break 30'					Coffee break 30'	Coffee break 30'
10:35 - 10:55		DEPO1-01-077 L. Villibord	DEPO3-01-047 G. Chetouh	DEPO3-01-121 P. Abarca	DEPO4-01-004 D. Hegeemann	DEPO5-01-082 M. Ezeblher	DEPO4-01-004 D. Hegeemann	ITEC2-01-135 R. van de Sanden	ITEC2-01-135 R. van de Sanden
10:55 - 11:15		DEPO1-02-031 Y. Wang	DEPO3-02-083 T. Nguyen	DEPO2-02-067 P. Zeman	DEPO4-02-040 M. Troia	DEPO5-02-109 A. Culet	DEPO4-02-040 M. Troia	ITEC2-02-034 C. Costin	ITEC2-02-034 C. Costin
11:15 - 11:35	11:00 - 12:40 Tutorial #2 <i>U. Cvelbar</i>	DEPO1-03-023 F. Ahangarani-Farahani	DEPO3-03-131 J-F. Pierson	DEPO2-03-019 A. Patelli	DEPO4-03-122 S.S. Kim	DEPO5-03-110 R. Costes	DEPO4-03-122 S.S. Kim	ITEC3-01-044 J. Barbé	ITEC3-01-044 J. Barbé
11:35 - 11:55		DEPO1-04-123 S-E. Benrazzouq	DEPO3-04-115 L. Marcinauskas	DEPO2-04-097 S. Chouteau	DEPO4-04-111 D. Plevic	DEPO5-04-020 P. Covin	DEPO4-04-111 D. Plevic	ITEC3-02-084 U. Cvelbar	ITEC3-02-084 U. Cvelbar
11:55 - 12:15		DEPO1-05-035 J. Carneiro de Oliveira	DEPO3-05-057 D. Kalanov	DEPO2-05-099 S. Kim	DEPO4-05-026 M. Segers	DEPO5-05-039 L. Janu	DEPO4-05-026 M. Segers	ITEC3-03-078 O. Touré	ITEC3-03-078 O. Touré
12:30 - 14:00	Lunch	Lunch (from 12:30)	Lunch (from 12:30)	Lunch (from 12:30)	Lunch (from 12:30)	Lunch (from 12:30)	Lunch (from 12:30)	Closing ceremony	Closing ceremony
14:00 - 14:40		<b>PL2 / M. CREATEORE</b>	<b>PL4 / R. ONO</b>	<b>PL6 / J. ALAMI</b>					
14:45 - 15:05	14:20 - 16:00 Tutorial #3 <i>R. Dussart</i>	GROM1-01-022 D. Babonneau	AMEL2-01-055 A. Bousquet	AMEL2-01-007 L. Zahedi	PSURF5-01-007 R. Dantime	MODIDD3-01-113 T. Minea	MODIDD3-01-113 T. Minea	MODIDD3-01-113 T. Minea	MODIDD3-01-113 T. Minea
15:05 - 15:25		GROM1-02-117 N. Fosseur	AMEL2-02-058 S. Konstantinidis	AMEL2-02-058 S. Konstantinidis	PSURF5-02-114 R. Dantime	MODIDD3-02-054 M. Farahani	MODIDD3-02-054 M. Farahani	MODIDD3-02-054 M. Farahani	MODIDD3-02-054 M. Farahani
15:25 - 15:45		GROM1-03-130 L. Zajickova	AMEL2-03-030 A. Dlop	AMEL2-03-030 A. Dlop	PSURF5-03-124 J-F. Coulon	MODIDD3-03-037 P. Vasina	MODIDD3-03-037 P. Vasina	MODIDD3-03-037 P. Vasina	MODIDD3-03-037 P. Vasina
15:45 - 16:15		Coffee break 20'	Coffee break 30'	Coffee break 30'	Coffee break 30'	Coffee break 30'	Coffee break 30'	Coffee break 30'	Coffee break 30'
16:15 - 16:45		GROM2-K1-045 A-L. Thomann	PSURF2-01-075 A. Tavermier	ITEC1-01-048 D. Bensalem	DEPO6-01-042 B. Menacer	MODIDD4-01-021 A. Helle	MODIDD4-01-021 A. Helle	MODIDD4-01-021 A. Helle	MODIDD4-01-021 A. Helle
16:45 - 17:05	16:20 - 18:00 Tutorial #4 <i>R. van de Sanden</i>	GROM2-01-005 A. Besnard	PSURF2-02-104 H. Beji	ITEC1-02-015 E. Haye	DEPO6-02-116 S. Calvez	MODIDD4-02-088 P. Vinchon	MODIDD4-02-088 P. Vinchon	MODIDD4-02-088 P. Vinchon	MODIDD4-02-088 P. Vinchon
17:05 - 17:25		GROM2-02-108 C. Mastel	PSURF2-03-046 R. Dussart	ITEC1-03-006 L. Valera	DEPO6-03-051 L. Coelho	NANO1-01-028 A. Anyan	NANO1-01-028 A. Anyan	NANO1-01-028 A. Anyan	NANO1-01-028 A. Anyan
17:25 - 17:45					DEPO6-04-120 M. Roggio	NANO1-02-076 J. Capek	NANO1-02-076 J. Capek	NANO1-02-076 J. Capek	NANO1-02-076 J. Capek
17:45 - 18:05		Poster session I (from 17:30 until 19:30)	Poster session II (from 16:35 until 18:30)	Poster session II (from 16:35 until 18:30)	DEPO6-05-061 S. Rubio	NANO1-03-086 M. Gireau	NANO1-03-086 M. Gireau	NANO1-03-086 M. Gireau	NANO1-03-086 M. Gireau
18:00 - 18:20		&			NANO1-04-052 N. Jacquot				
18:30 - 20:00	Registration/Badge pick up & Welcome reception until 20:00	Industrial evening (from 18:30 until 20:30)	Industrial evening (from 18:30 until 20:30)	Industrial evening (from 18:30 until 20:30)	Conference dinner cocktail from 19:30				

Topics:

AMELI GROM

MODIDD DEPOS

NANO PSURF

ITEC

Poster sessions, exhibition, coffee breaks & lunches are located in the Gould area